



imec

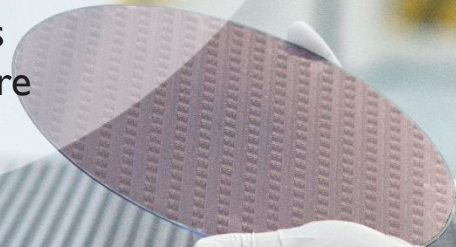
The environmental impact of IC chip manufacturing
Sustain-E Summer School – Thu June 19 2025

Cédric Rolin

Program Manager Sustainable Electronics

imec

- Founded in 1984 in Leuven, Belgium
- Independent non-for-profit organization
- Europe's largest nano/micro-electronics research center
- 846 million € revenue in 2022
 - 69% industry, 24% regional government, 7% EU & regional program
- Collaboration with >600 companies and >200 universities
- >6500 people working at imec of which >500 residents
- >3 billion € infrastructure
- >120 spin-offs created



World-class infrastructure

Hyperspectral imaging lab & demo room
Integrated imagers lab
Smart sensor lab
ExaScience lab

RF & high-power lab
Photonics labs

Labs:
measurement,
testing, GaN

Lifescience labs

Material and device
characterization
labs

200mm cleanroom

- Silicon pilot line for prototyping and low-volume mfg
 - iSiPP200 and iSiPP50G photonics prototyping platform
 - 200mm GaN-on-Si platform
 - Quantum computing lab
 - Materials & interface lab
- 5,200m²

300mm cleanroom

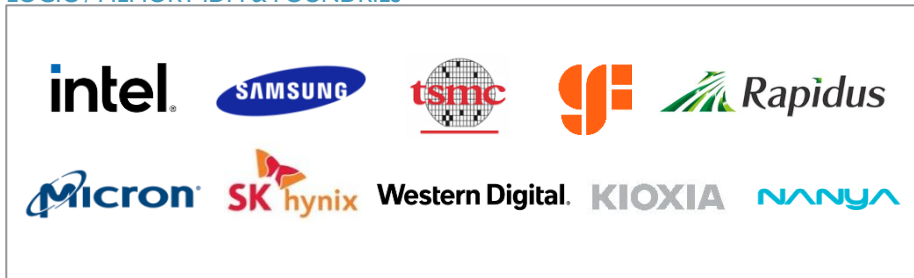
- (High-NA) EUV, Attolab, advanced patterning
- State-of-the-art etch, implant, cleaning, metrology, deposition, ... equipment from leading-edge OEMs
- Ballroom type of cleanroom (7,200m², Class 1,000)
- 24/7 operational

Bio labs

- Cell & tissue culture labs
- Optical labs
- Wet chemistry labs
- Clinical labs
- Pre-PCR lab
- Neuropixels lab

CORE CMOS ECOSYSTEM PARTNERS - 2024

LOGIC / MEMORY IDM & FOUNDRIES

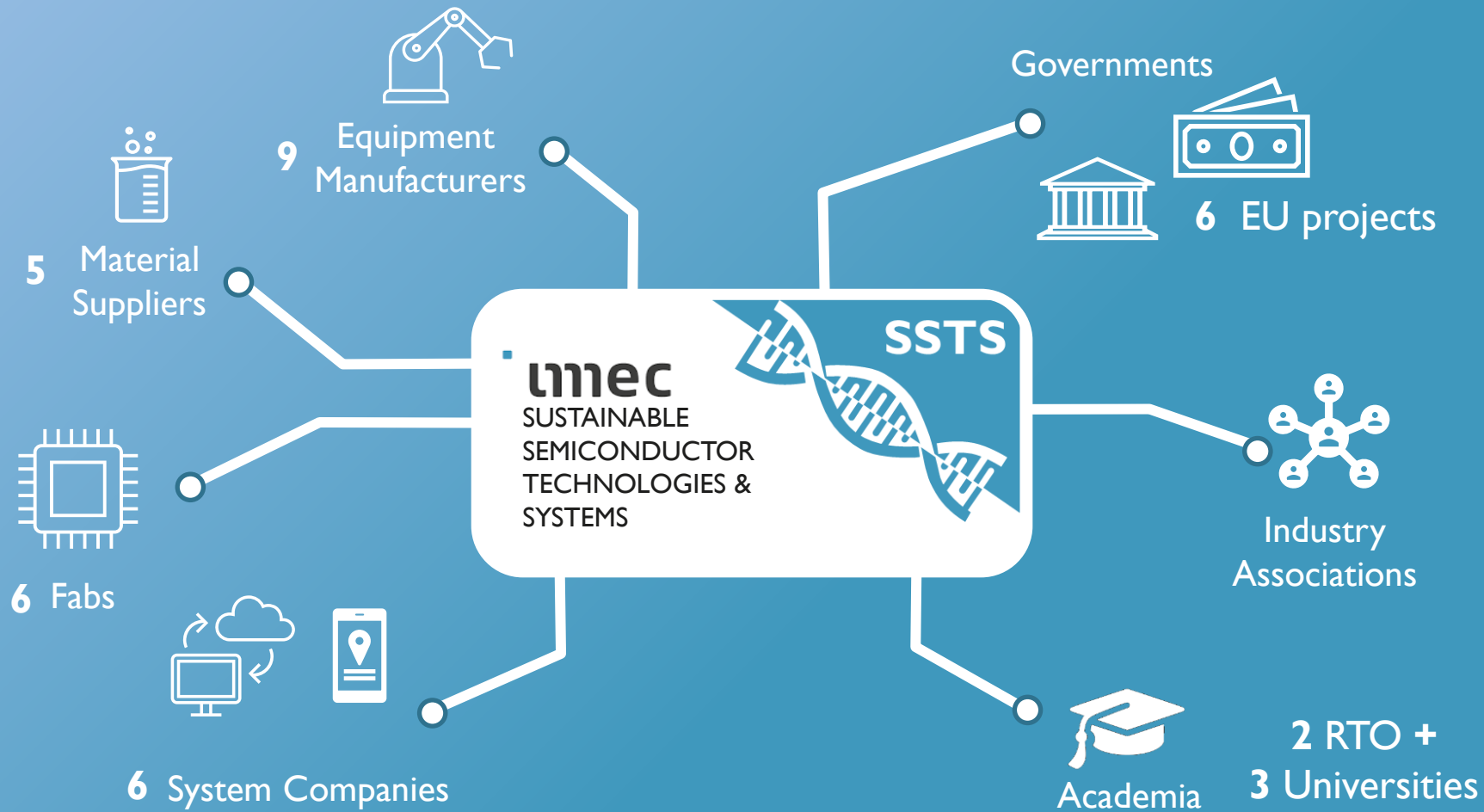


FABLESS / FABLITE / SYSTEM / EDA



EQUIPMENT & MATERIAL SUPPLIERS / OSAT



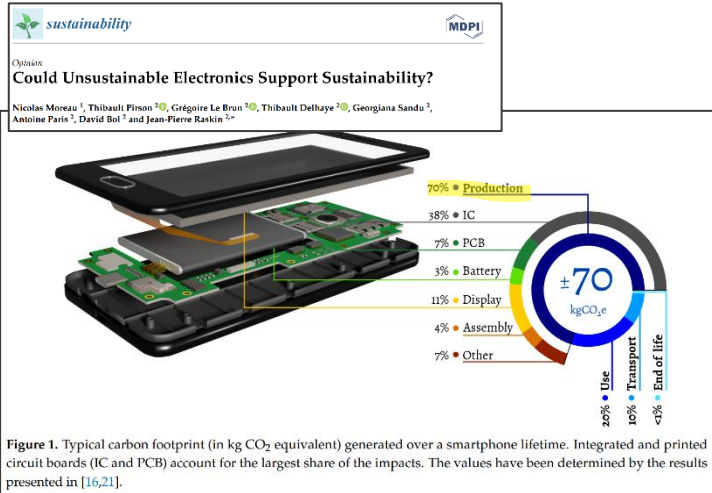


Our mission: Help the IC manufacturing value chain reach its environmental sustainability targets

Macro view: the impact of the semiconductor industry

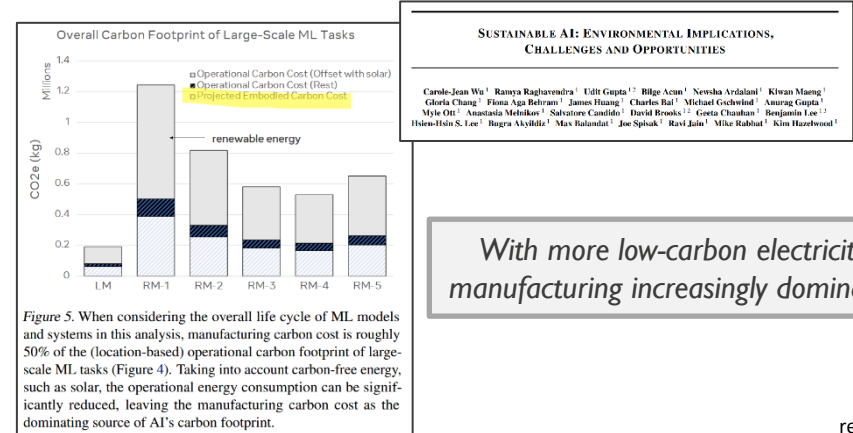
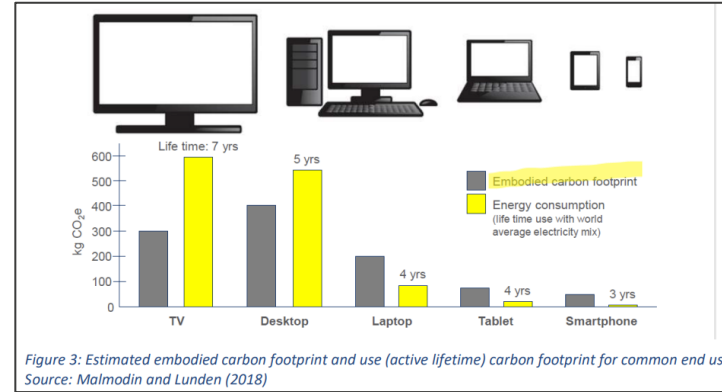
Scope: focus today is on IC manufacturing

How does it compare to the use phase? → Product-dependent, but never negligible



Coarse rule of thumb:

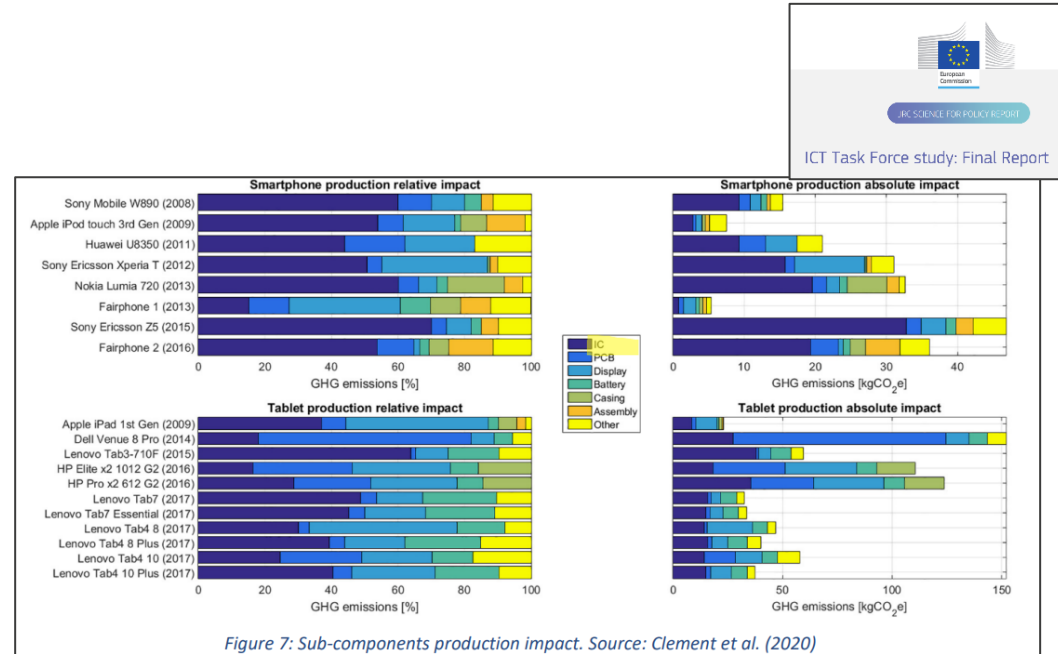
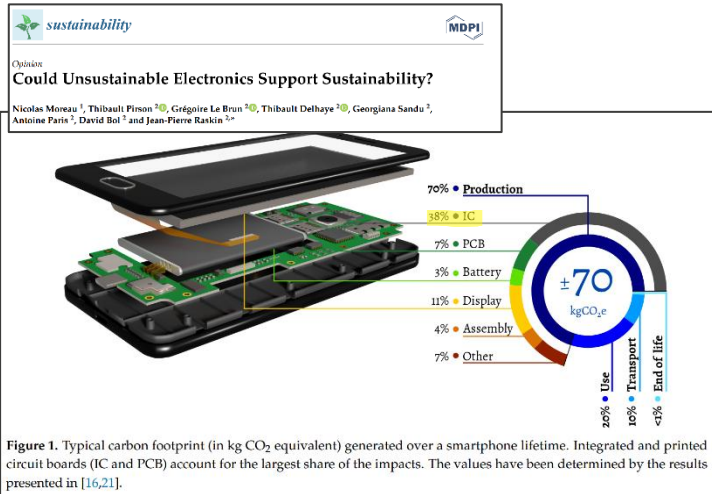
- For portable devices → manufacturing is ~70%
- For datacenters → manufacturing is ~30%



With more low-carbon electricity, manufacturing increasingly dominates

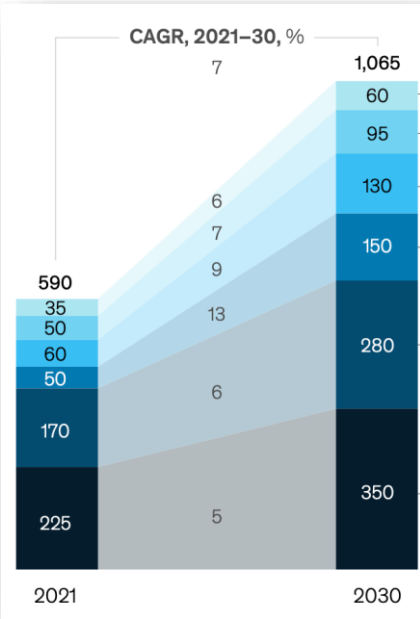
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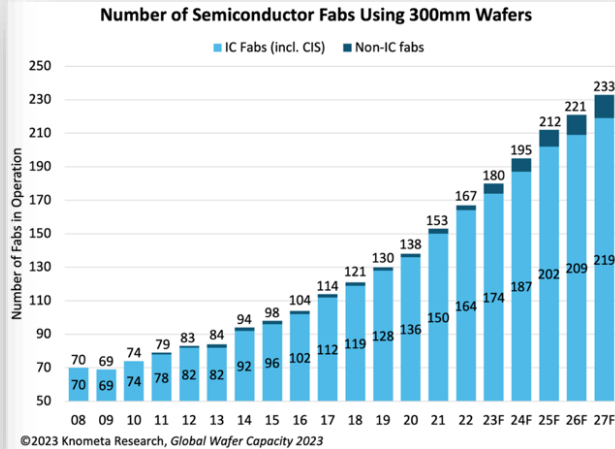


Challenge 1: Semiconductor industry is growing fast

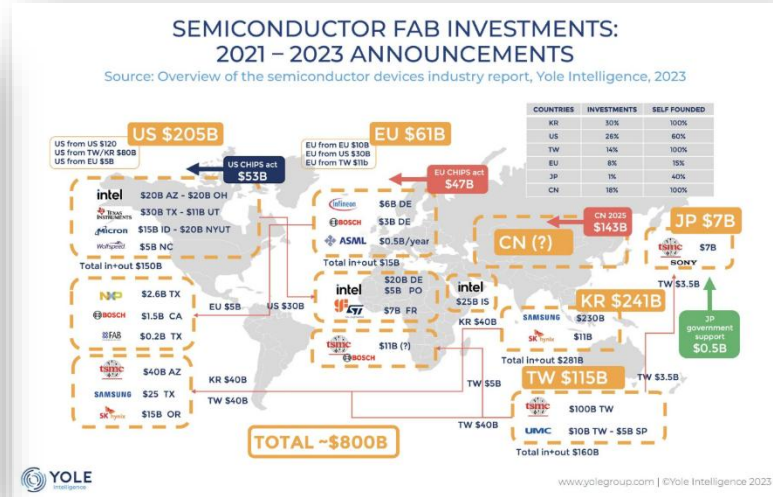
Boosted by Chips Acts, many Fabs scheduled to open despite current market weakness



Strong projected growth



More 300mm Fabs

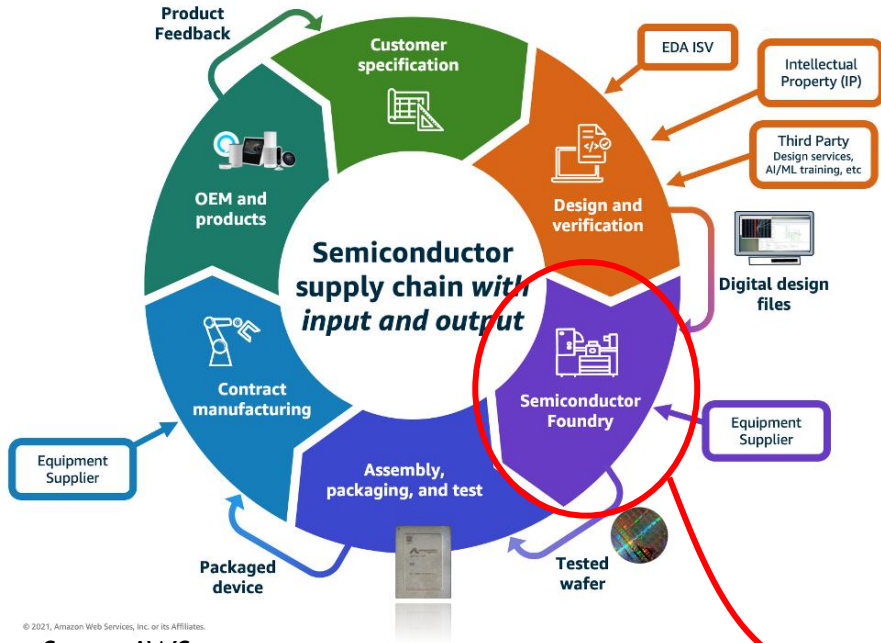


Massive funding

Source: Chip Industry Heads Toward \$1T (semiengineering.com)

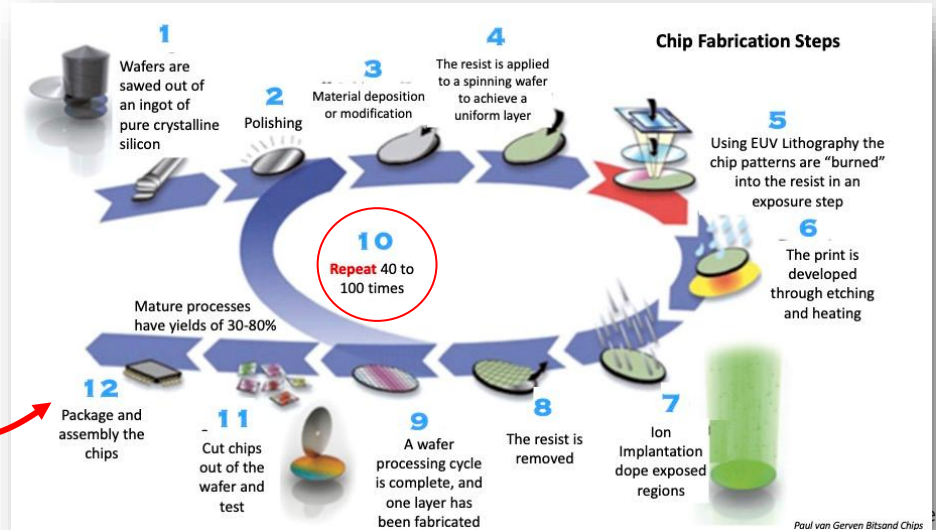
Challenge 2: IC technology is complex

IC chips = most complex mass-produced objects



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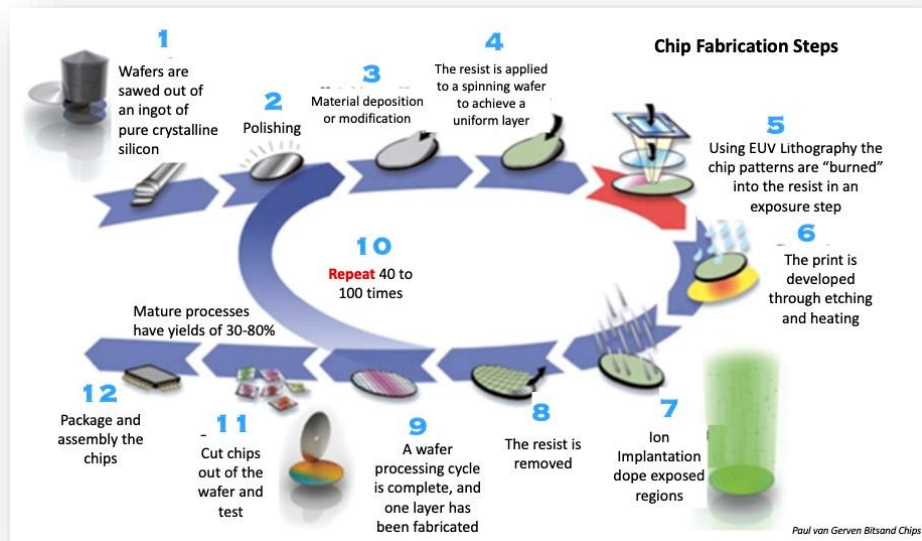
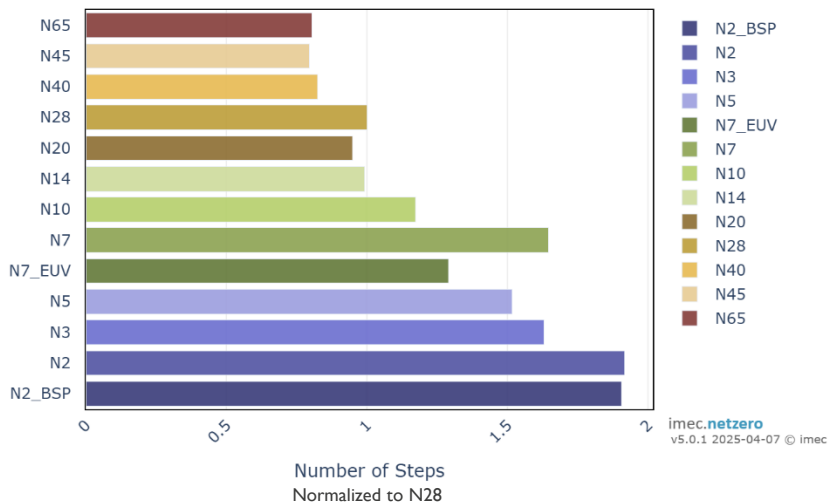
Source: AWS



Challenge 2: IC technology complexity increases

Normalized number of process steps

Comparison of Number of Steps by Technology for full flow (official)

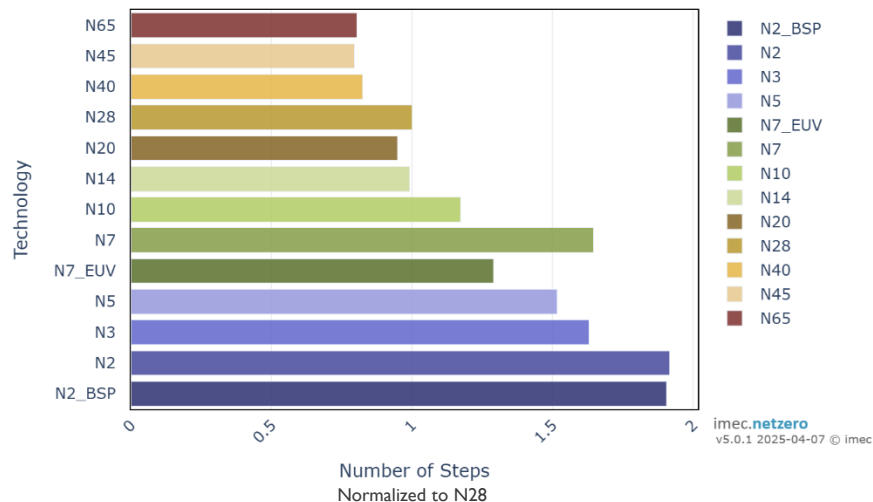


Challenge 2: IC technology complexity -and emissions- increase

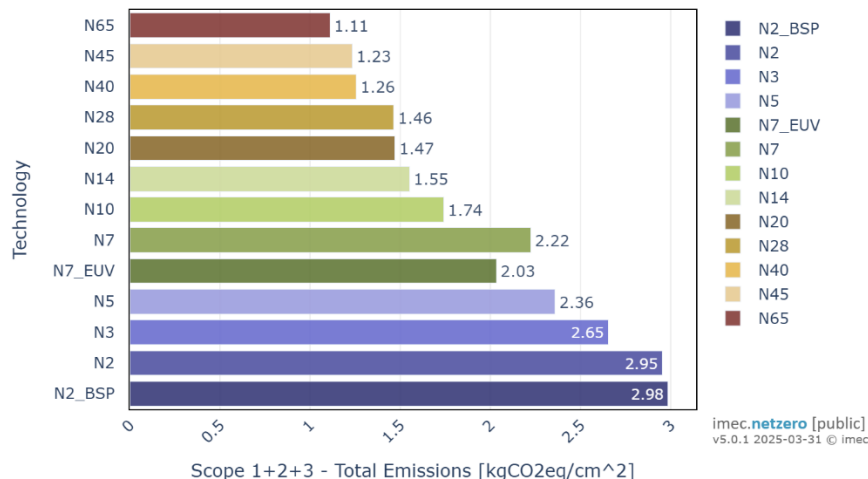
Normalized number of process steps... correlates well with emissions

We'll come back to that

Comparison of Number of Steps by Technology for full flow (official)

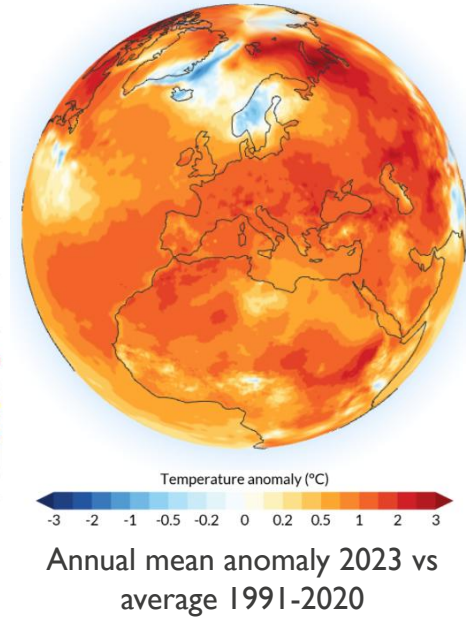
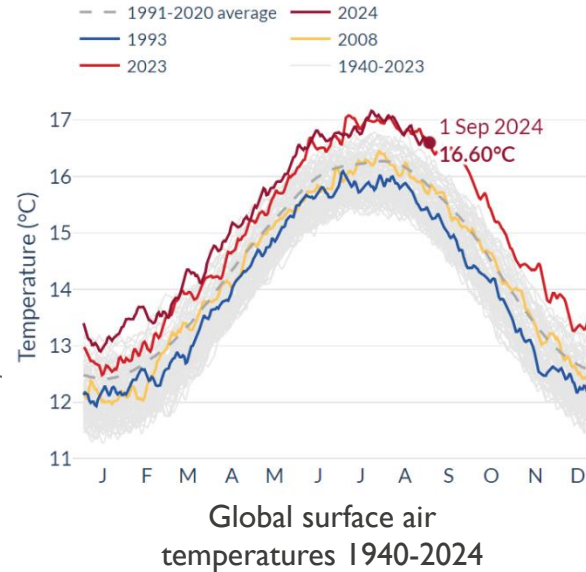
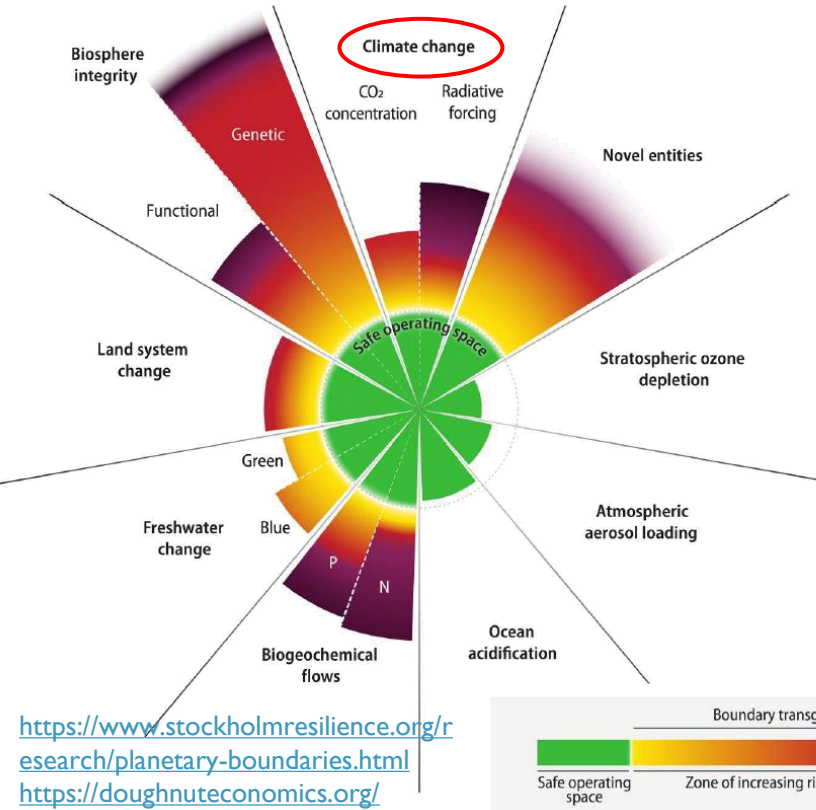


Comparison of Scope 1+2+3 - Total Emissions [kgCO₂eq/cm²] by Technology for full flow



Areas of concern for semiconductor industry – Climate Change

9 planetary boundaries



Data: ERA5 / Credit: C3S/ECMWF
WebApp: <https://pulse.climate.copernicus.eu/>

<https://www.stockholmresilience.org/research/planetary-boundaries.html>
<https://doughnuteconomics.org/>

CO₂ Emissions from Semiconductor Industry in Perspective

~ 36 billion tons



World-wide

Sources: Liu et al. Nature reviews earth & environment 2023 (Fossil fuels and Cement only)

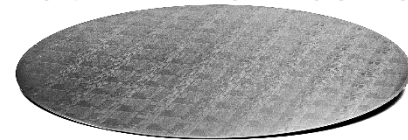
~ 1,2 billion tons



ICT Industry

Source: Freitag, C. Et al. 2021.
<http://arxiv.org/abs/2102.02622>

~ 185 million tons



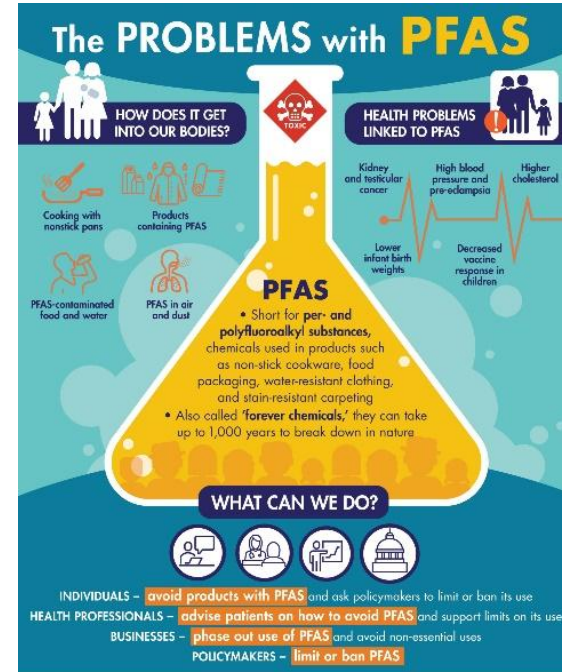
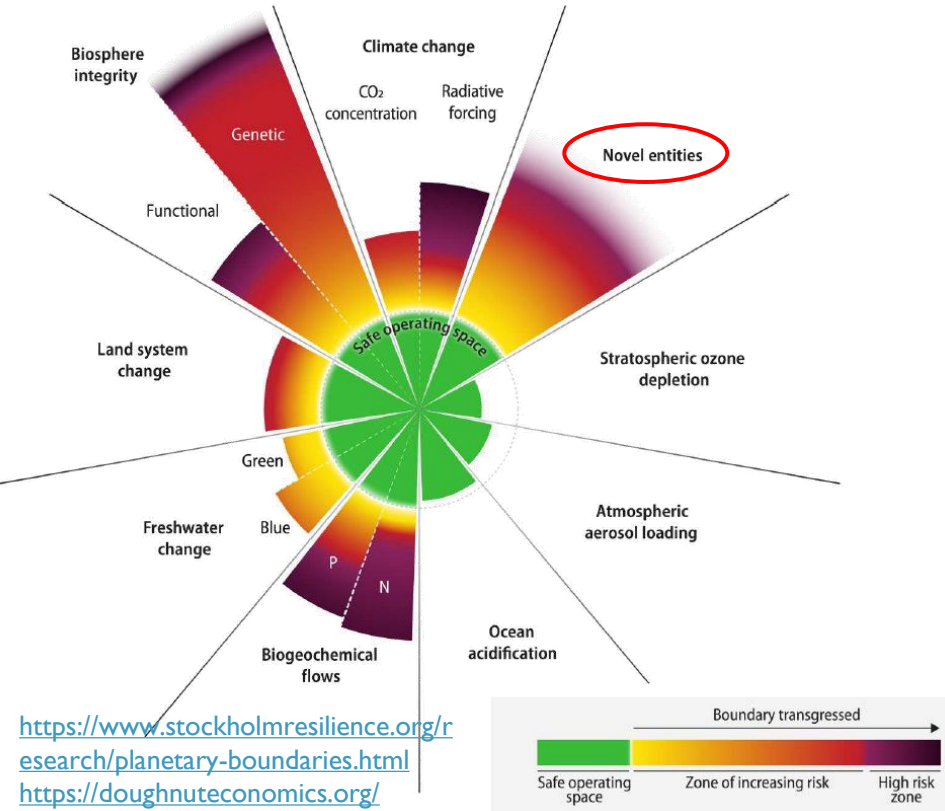
Semiconductor
manufacturing

Includes Scope 1, scope 2 and scope 3 consumables and services. For industry in 2021.

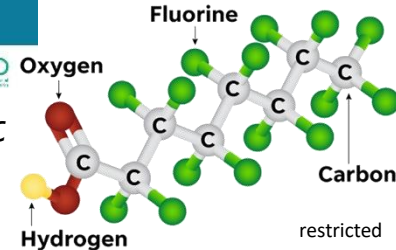
Source: SEMI SCC Whitepaper on Transparency, Ambition, and Collaboration - 2023

Areas of concern for semiconductor industry – Novel entities

9 planetary boundaries

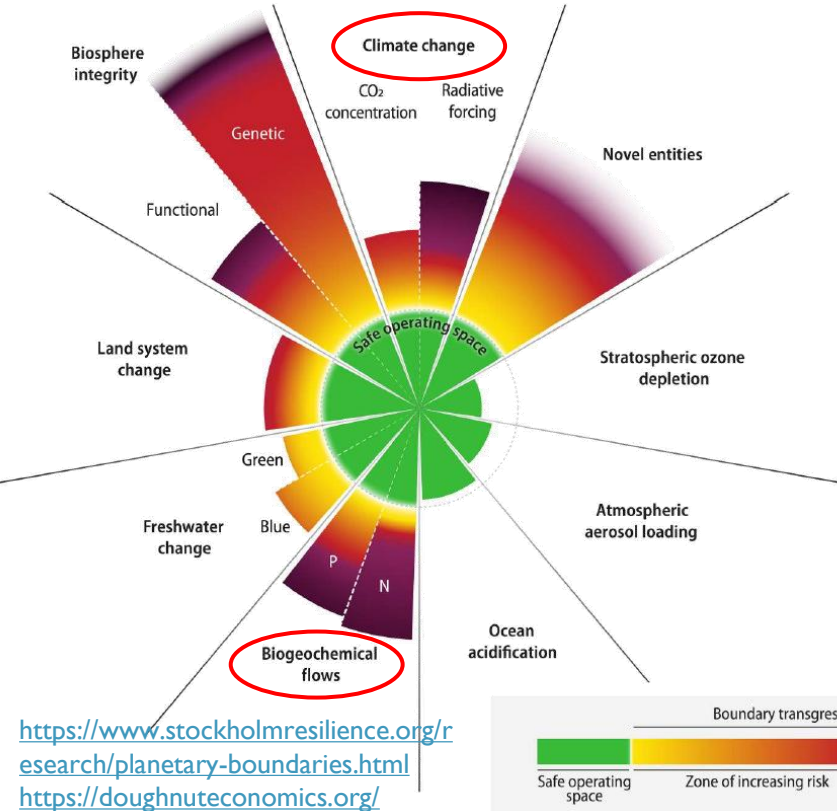


Perfluorooctanoic Acid (PFOA)



Areas of concern for semiconductor industry – Material Sourcing

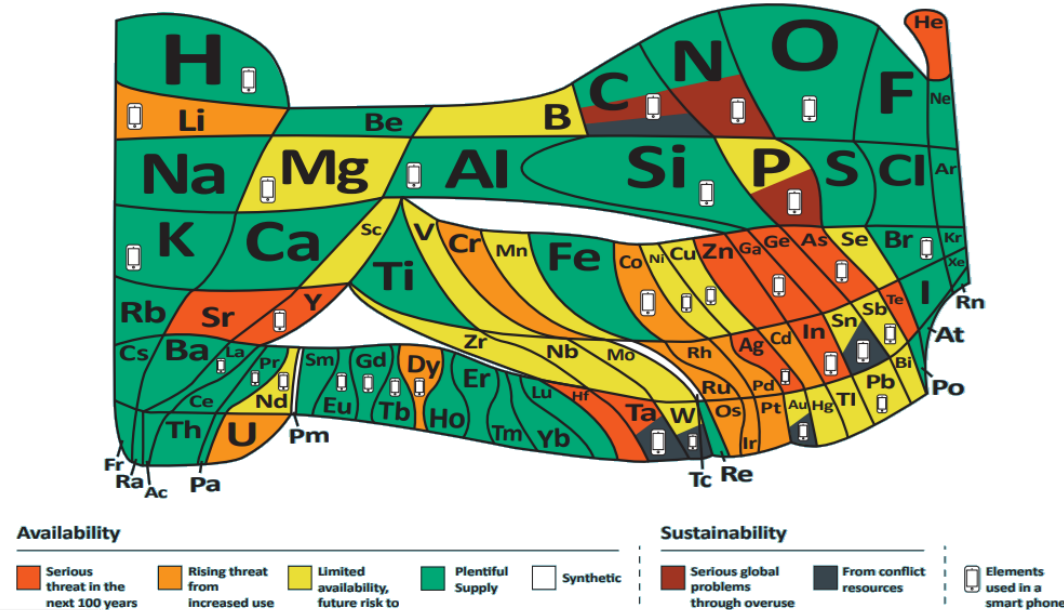
9 planetary boundaries



Resource depletion and geopolitical tensions

The 90 natural elements that make up everything

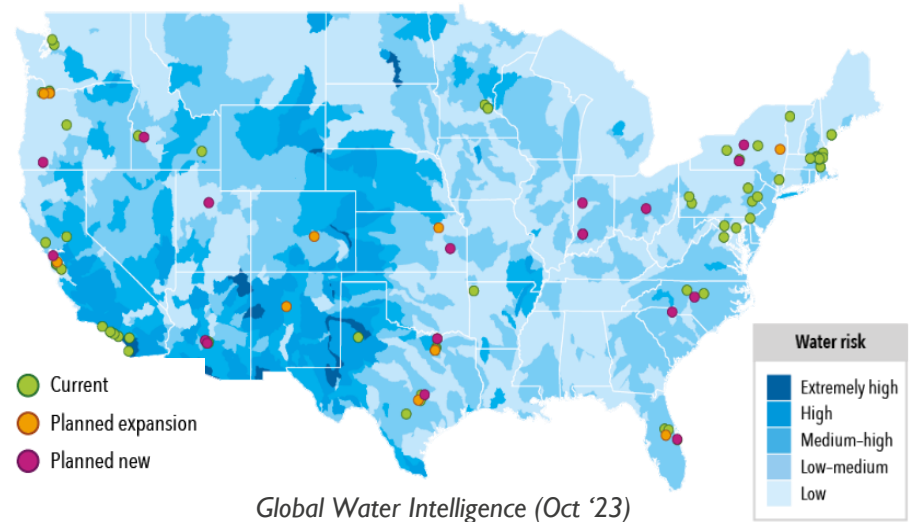
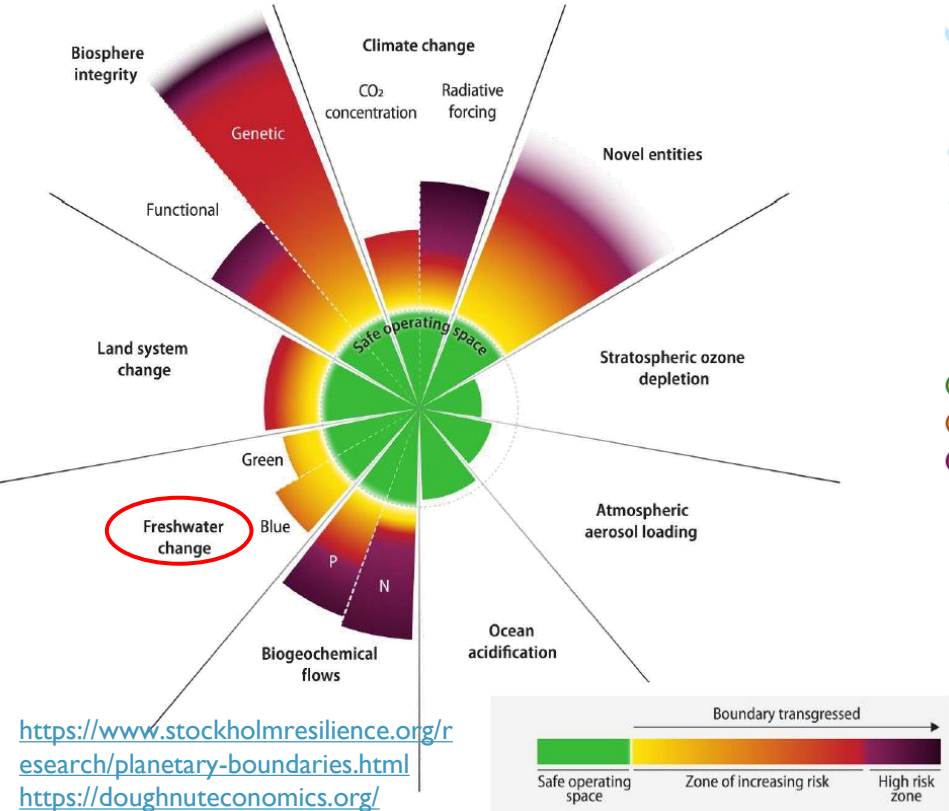
How much is there? Is that enough? Is it sustainable?



<https://www.euchems.eu/euchems-periodic-table/>

Areas of concern for semiconductor industry - Water

9 planetary boundaries



Chipmakers in drought-hit Taiwan order water trucks to prepare for 'the worst'

Reuters (Feb '21)

There is strong ambition in the sector...

News - 28 August, 2023

ASM first in semiconductor industry to have net-zero target verified by SBTi

Almere, The Netherlands
August 28, 2023

[Press releases | ASM](#)



Advanced materials for sustainable electronics

April 21, 2023

[Press release Air Liquide](#)



Transparency, Ambition, and Collaboration:

Advancing the Climate Agenda of the Semiconductor Value Chain

[SCC White Paper](#)



Semiconductor
Climate Consortium

Apple unveils its first carbon neutral products

PRESS RELEASE • September 12, 2023

The new Apple Watch lineup marks major progress toward ambitious Apple 2030 climate goal



[Product Environmental Report](#)



January 31, 2023

[Press Release Amazon](#)




Amazon Sets a New Record for Most Renewable Energy Purchased by a Single Company

TSMC Accelerates Renewable Energy Adoption and Moves RE100 Target Forward to 2040

Issued by: TSMC
Issued on: 2023/09/15



[Press release TSMC](#)

 [TSMC Accelerates Renewable Energy Adoption and Moves RE100 Target Forward to 2040](#)

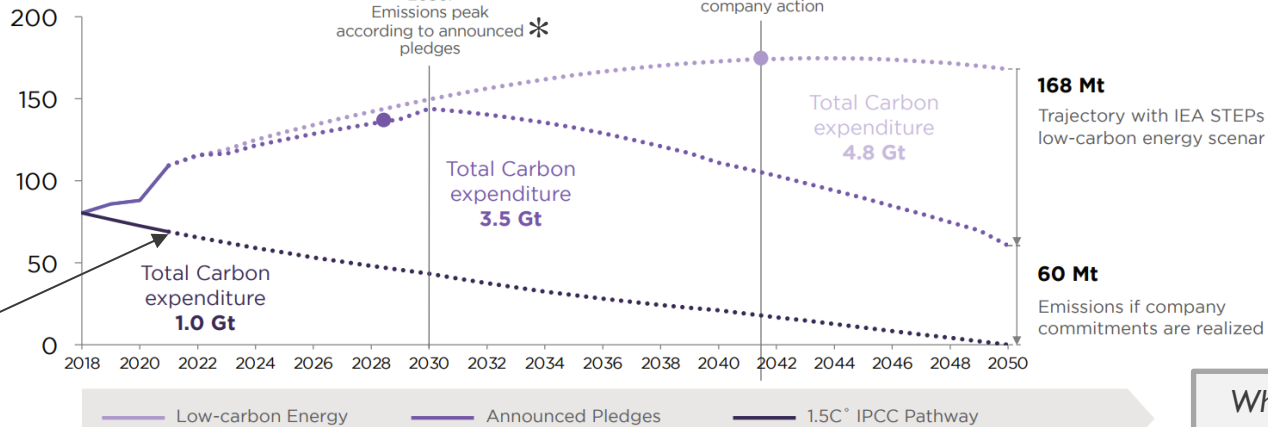
There is strong ambition in the sector.. But more is likely needed

Announced* pledges: estimated reduction of ~30% (but we need 100%)

Exhibit 7:

Announced sustainability pledges reduce total 2019–2050 emissions by 30% and are within 60 Mt CO₂e of 2050 net zero

Manufacturing Emissions
(Mt CO₂e)



1 Emissions growth based on projected capacity growth (3.25%) and average intensity growth (1.01%), all else constant
Note: Low-carbon energy scenarios use IEA STEPS for North America, Europe, and Asia-Pacific. Source: BCG analyses on data from: CDP, imec, SEMI, IEA

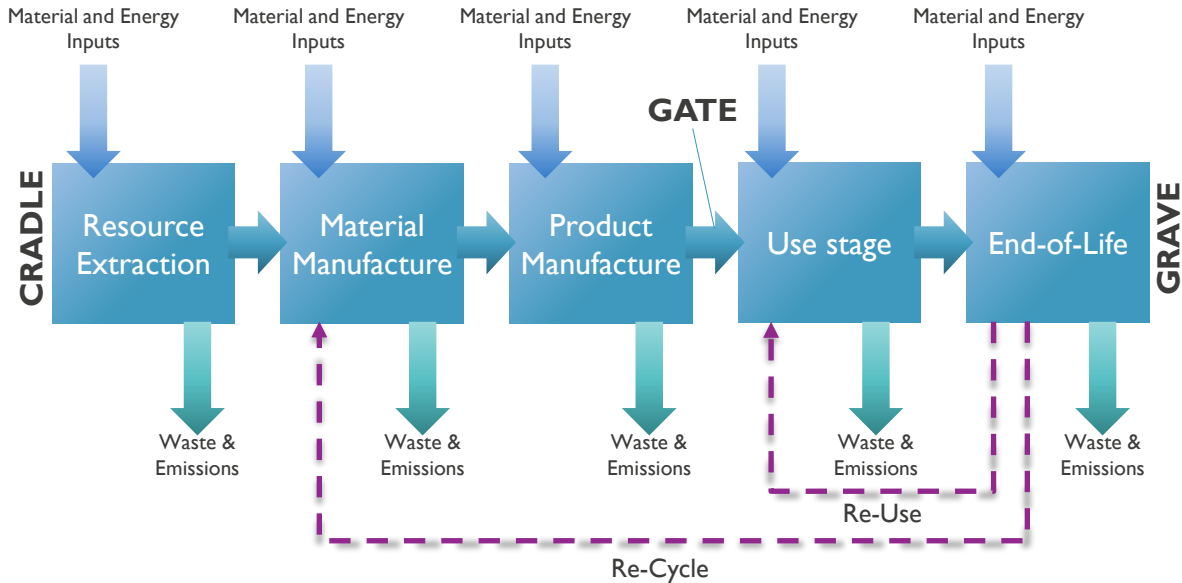


What would be required to close the gap?

Intermezzo: A detour to LCA theory

Life-Cycle Assessment (LCA) in a nutshell


*“A methodology for the assessment of the **environmental impacts** associated with all the stages of the life cycle of a **product** or a **service**”*



Holistic approach: Don't shift the burdens!

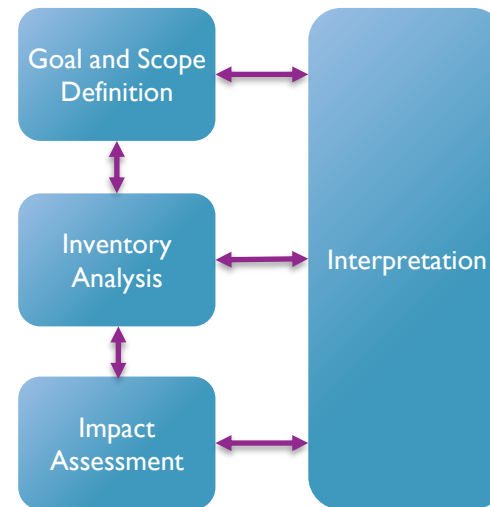
Life-Cycle Assessment (LCA) in a nutshell

Motivation for LCA

- 
- **Compliance:**
Meet legal requirements
 - **Market driven:**
Meet customer requirements
 - **Engaged:**
Identify improvement opportunities through value chain
 - **Shape the future:**
Inform Eco-design at an early stage

Resources
Engagement
Stewardship

General phases of LCA

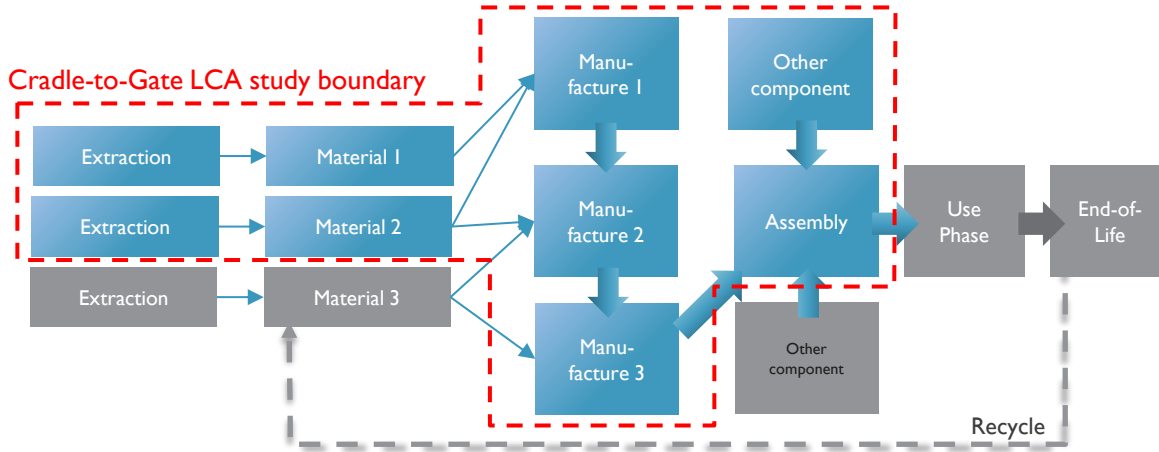


From ISO 14040 and ISO 14044 standards

Goal and scope

Set the stage for LCA study by defining:

- The **product system** and its **functional unit (FU)**:
“A quantifiable unit that meets the function requirements”
- The reference **flow** and the **system boundaries**



Removing a process must be motivated:

- Out-of-scope of the study
- Known to be negligible
- Lack of information

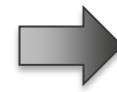
- The **impact assessment** metrics

“What impact will the study characterize ?”



Life-cycle inventory (LCI)

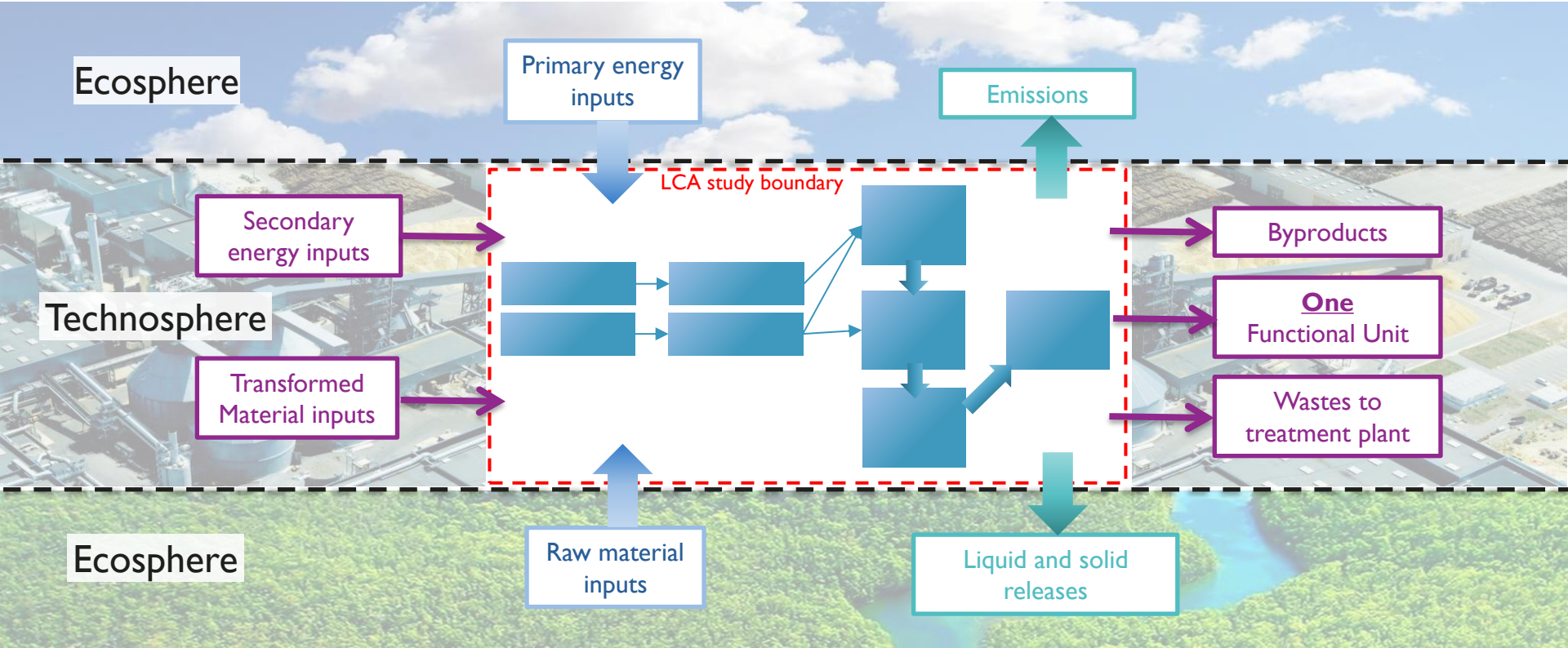
Record all the input and output flows



Elementary Flows from/to EcoSphere

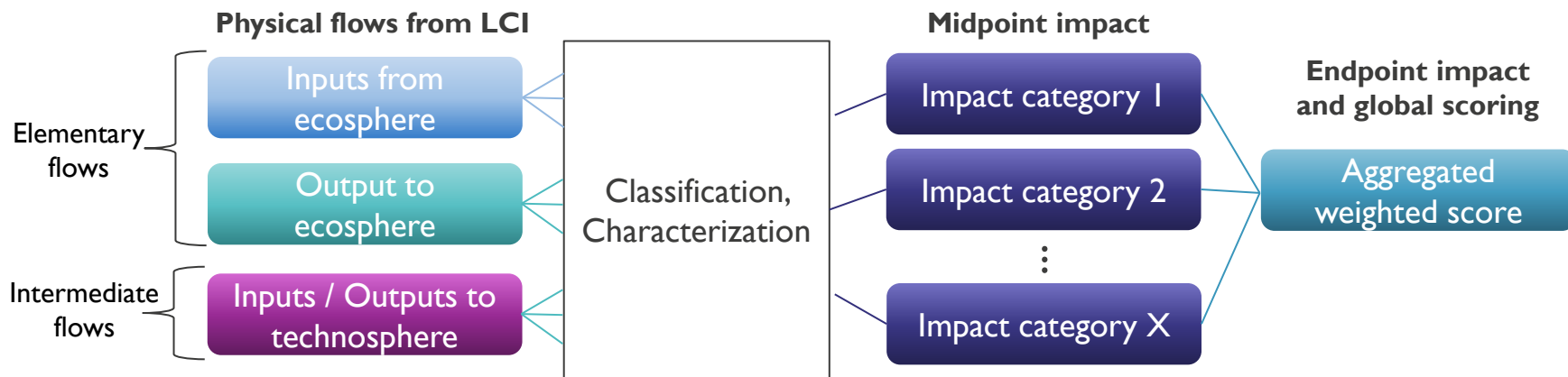


Intermediate Flows



Life-cycle impact analysis (LCIA)

Evaluate the impact



Examples

Impact category	unit	Flow of interest	Characterization factor
Climate Change	$\text{kg}_{\text{CO}_2,\text{eq}} / \text{FU}$	All gas released to the atmosphere that yield radiative forcing (GHGs)	Global Warming Potential at 100 years (GWPI00) in $\text{kg}_{\text{CO}_2,\text{eq}} / \text{kg}_{\text{GHGgas}}$
Abiotic Resource Use	$\text{kg}_{\text{Sb,eq}} / \text{FU}$	Metal and Mineral resources extracted from the ecosphere	Abiotic Depletion Potential (ADP) $\text{kg}_{\text{Sb,eq}} / \text{kg}_{\text{mineral}}$
Water Scarcity Footprint	m^3 / FU	Input water consumption	Water Scarcity Index (WSI) $\text{m}^3\text{-withdrawal} / \text{m}^3\text{-available}$. Regional dependence.

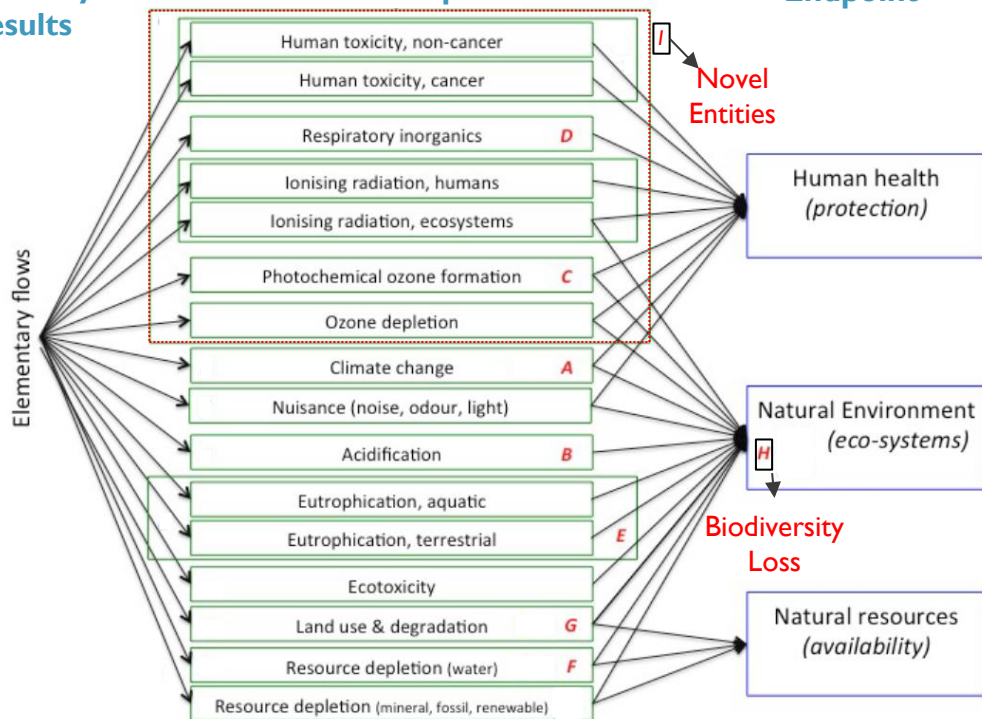
Embracing the complexity of impacts

Impact indicators beyond climate change...

Inventory
results

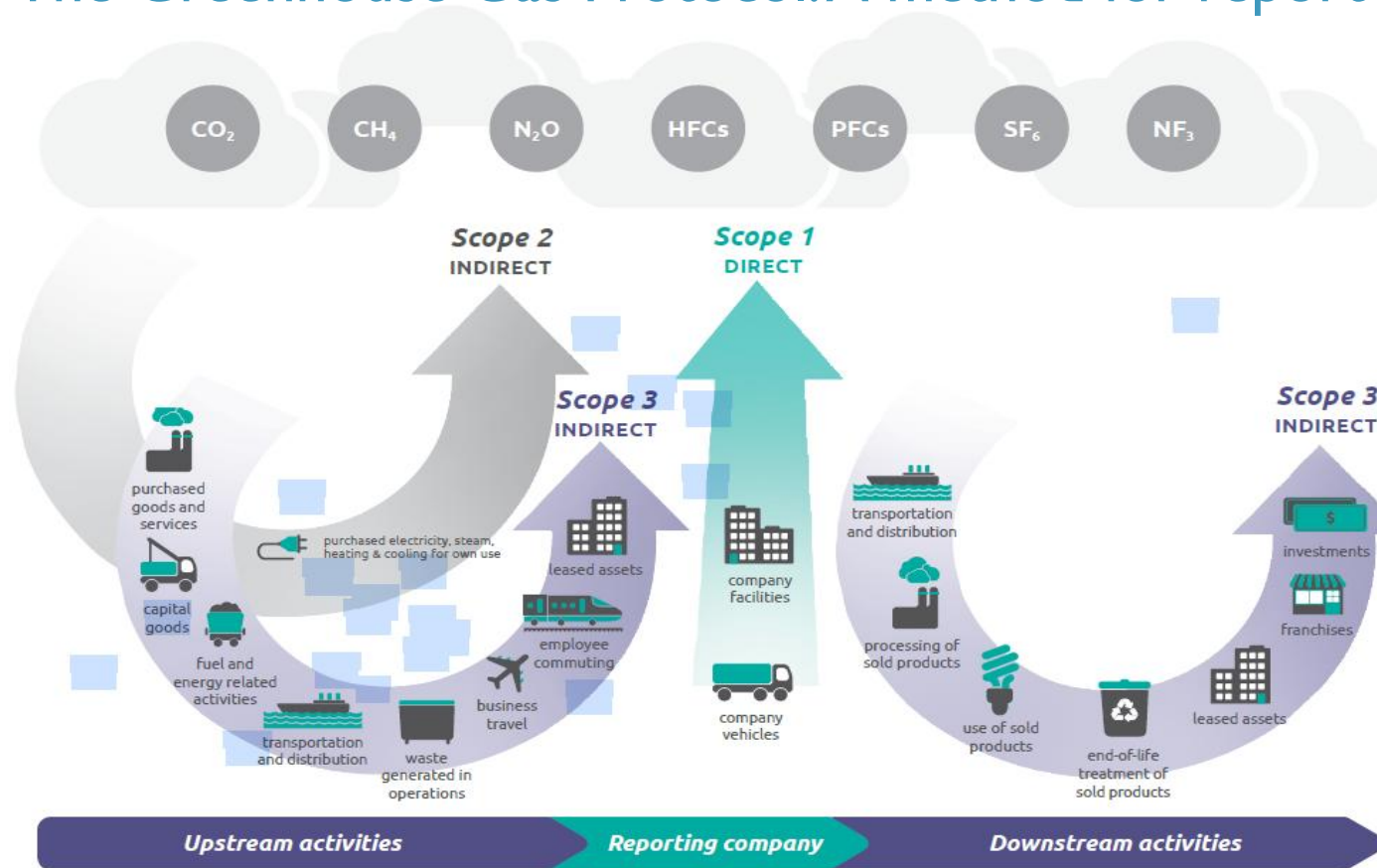
EF3.1 Midpoint

Endpoint



- EC-JRC **EF3.1** framework defines:
 - **3** Endpoint indicators as generic Areas of Protections
 - **16** Midpoint indicators capture a broad diversity of impacts
- Planetary Boundaries **A to I** fit in a broader set of impact indicators
- Implementing EF3.1 in our modelling to offer a **full Impact Analysis** beyond Climate change only

The Greenhouse Gas Protocol: A method for report **GHG emissions**



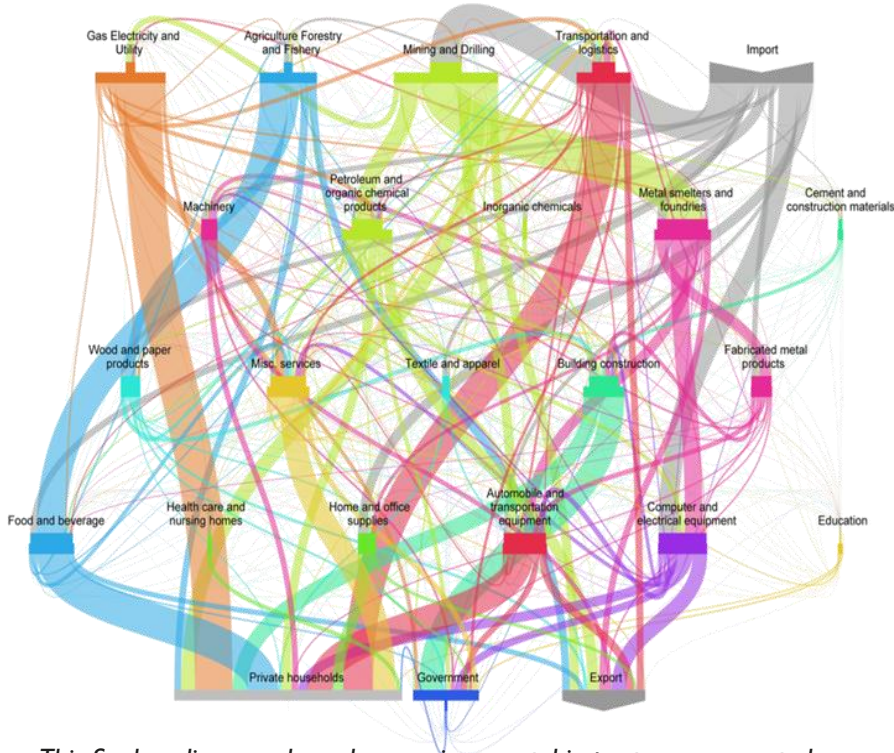
Very useful when discussing Carbon Footprint in context of:

- **Product Carbon Footprint** calculation
- **Corporate Carbon Accounting**

But **Climate Change Only !**

This reporting method can be realized using LCA. But other methods exist for quantifying emissions

LCA in practice



This Sankey diagram shows how environmental impacts are generated and passed down throughout the supply chain of the U.S. economy.

<https://vitalmetrics.com/types-of-life-cycle-assessment>

- LCA is the preferred method for **quantitative environmental impact assessment**.
- The path can be tortuous and the final results are influenced by the analysis choices:
 - **Systematic** following of the LCA guidelines is needed
 - **Transparency** in the methodology is required.

Data is the new gold:

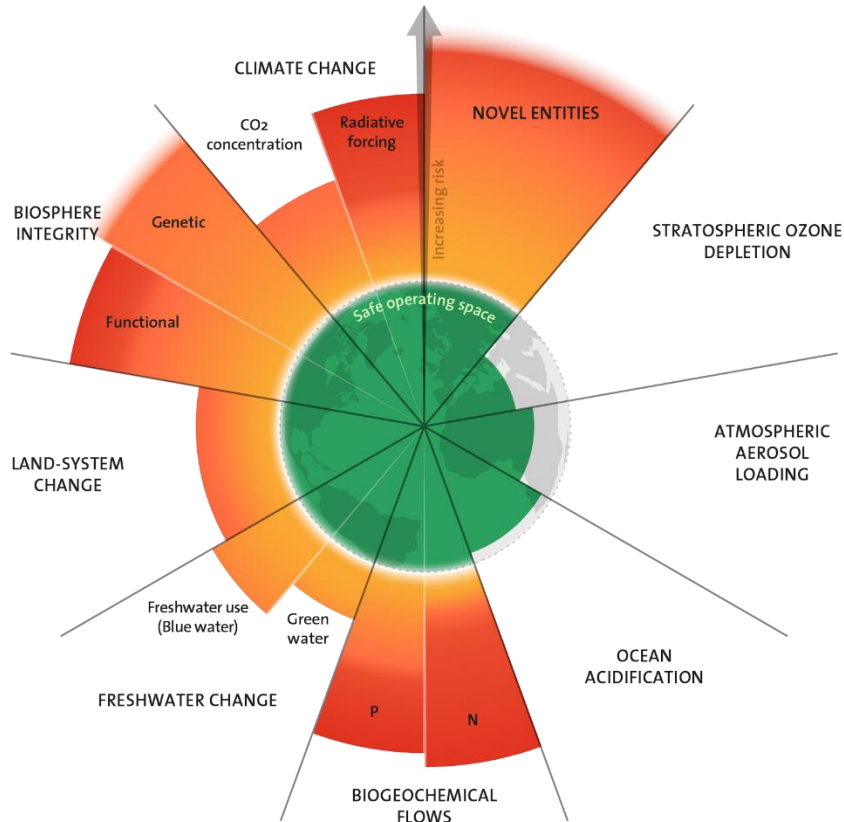
- Data quality is essential, yet practitioner must prefer **data completeness over data accuracy**. **Bridging data gaps** often requires creativity and dedication:
 - In primary data collection
 - Selection of secondary data
 - Usage of proxies as temporary replacement

LCA implemented through:

- **Large-scale datasets** of secondary data (e.g. Ecoinvent).
- **Softwares** (OpenLCA, SimaPro, GaBi, Activity Browser) that deploy the methodology.

Planet boundaries

Climate change is not the only indicators regarding environmental impact

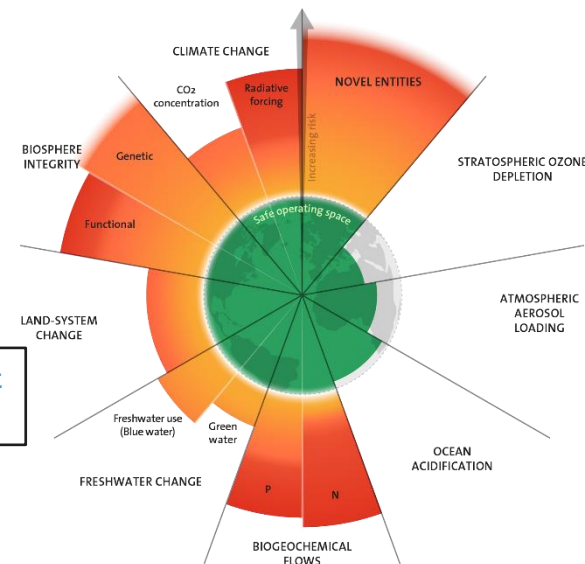


- Climate change is the most famous indicators regarding environmental impact
 - Well documented
 - Studied for a long time (first IPCC report in 1990)
 - Based on well studied physical phenomenon (GWP)
- 6 / 9 planetary boundaries are transgressed → “Earth is well outside of the safe operating space for humanity”
→ Other indicators should be considered!

LCA indicators

Different sets of indicators exist

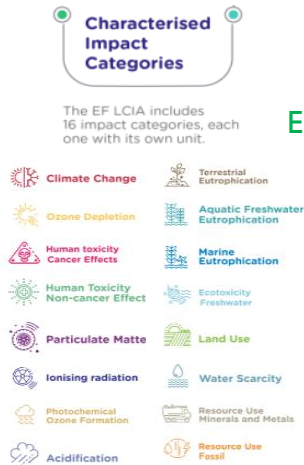
- CML
- ReCiPe
- IPCC
- EF
- ...



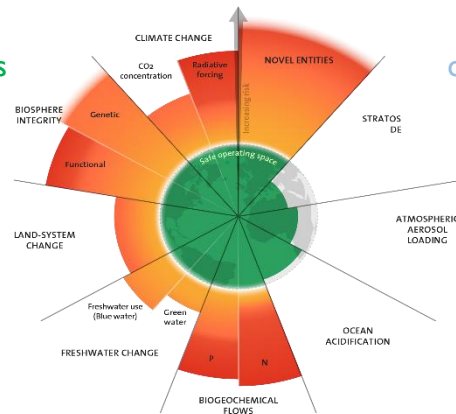
LCA limits

LCA studies environment impact, not sustainability

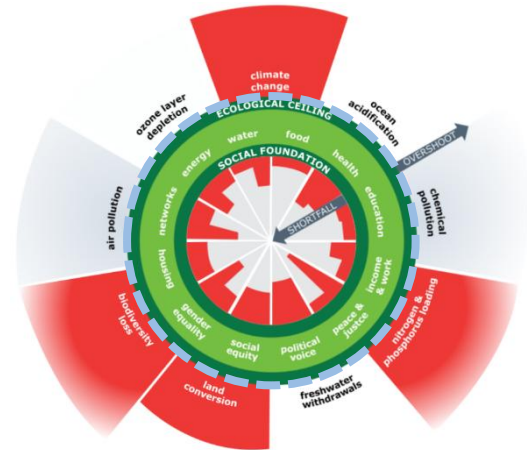
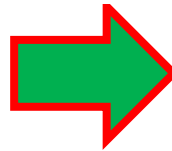
- LCA used in isolation remains a relative tool shaping innovation beyond Planetary Boundaries (PB)
- Absolute LCA can be used to define the ceiling of the Doughnut leading to sustainability following Kate Raworth's theory



Midpoint and
Endpoint impacts
translate into
PBs



PBs set the
ceiling to our
economy

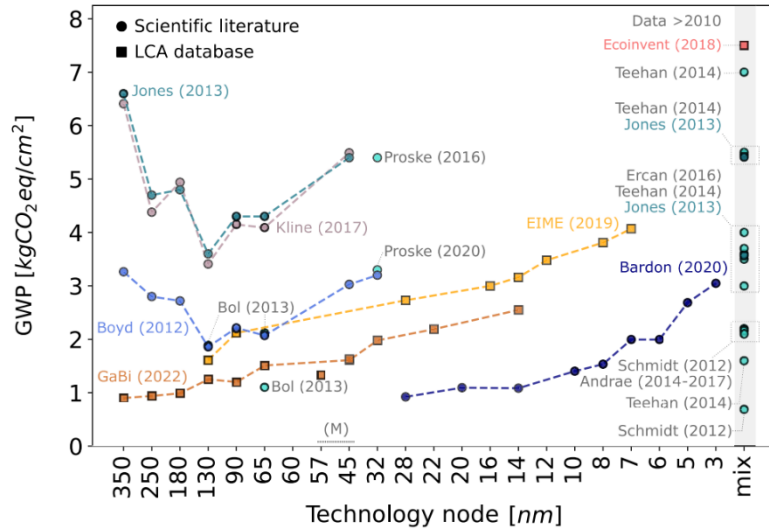


Doughnut | Kate Raworth

EF 3.1 impact

Micro view: hotspots in semiconductor manufacturing

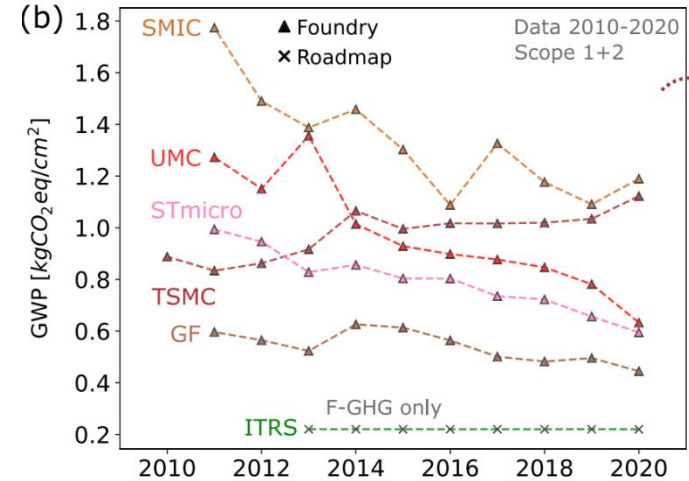
Current LCI situation: varied and outdated



Literature and LCA database data:

- Variable scope
- Variable sources (primary vs. secondary)
- Variable approaches (e.g. bottom-up vs top-down)
- Data gaps require “creative” plugging methods

Source: Pirson et al., 2023 – The Environmental Footprint of IC Production: Review, Analysis, and Lessons From Historical Trends

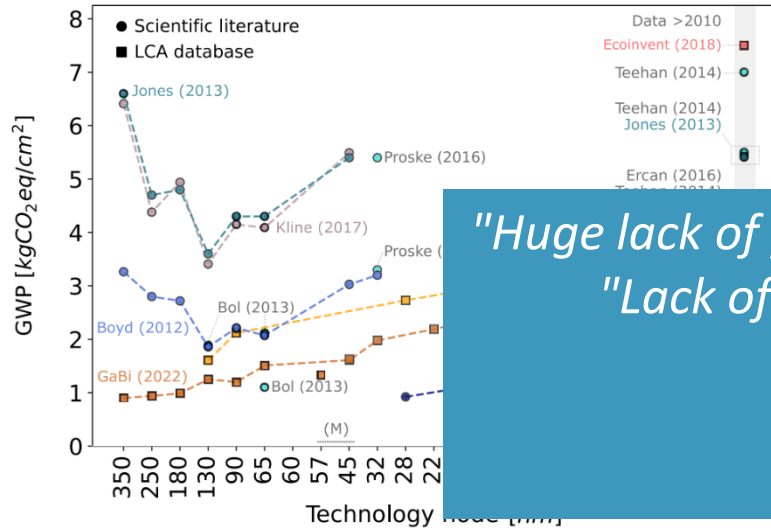


Industry data from public corporate social responsibility report:

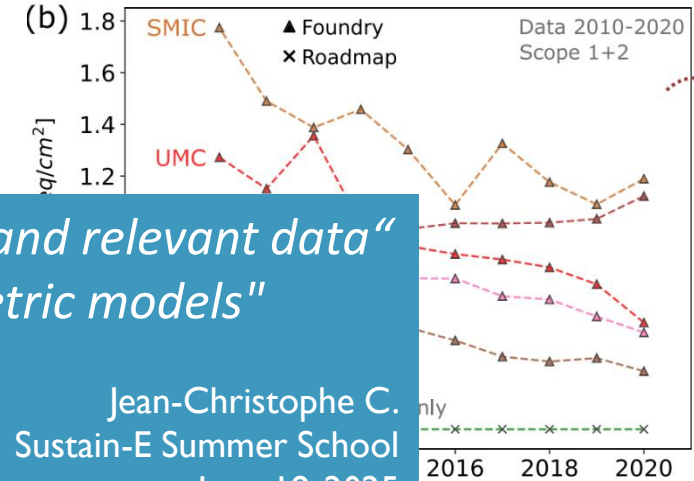
- Top-down, primary sourced data
- Aggregated over entire company operation, not “per chip” or “per-node”
- Limited scope
- Non-transparent methodology

GWP: Global Warming Potential

Current LCI situation: varied and outdated



"Huge lack of precise and relevant data"
"Lack of parametric models"



Jean-Christophe C.
 Sustain-E Summer School
 June 18, 2025

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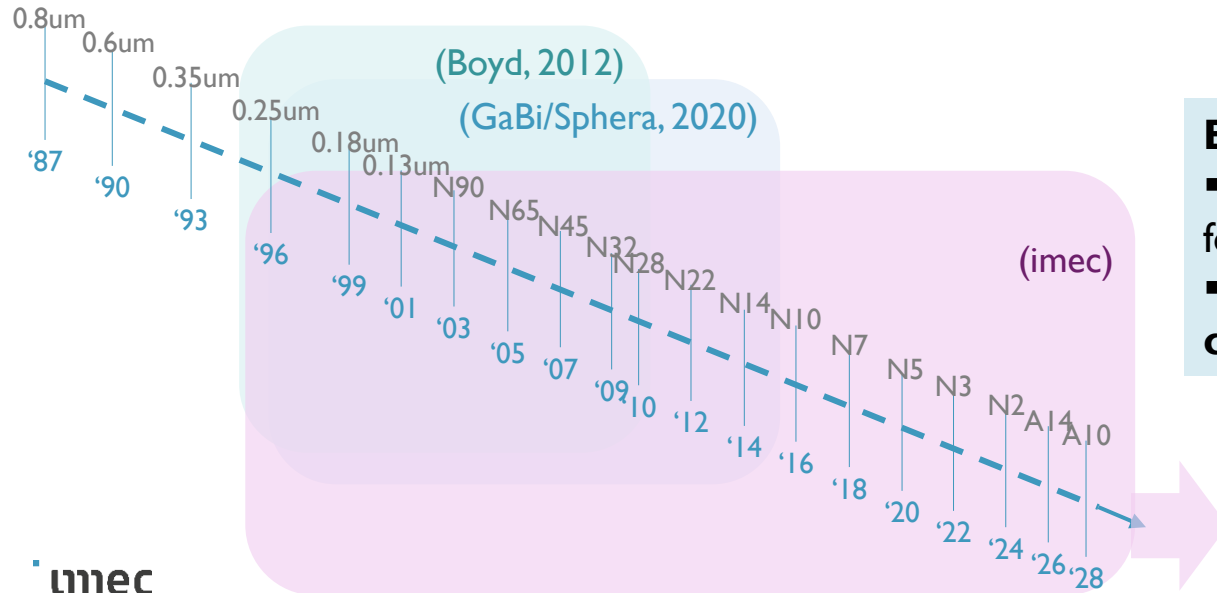
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GWP: Global Warming Potential

Imec ambition for the SSTS Assess pillar

Close the data gap by providing quality, transparent data on environmental impact of IC chip fabrication in a generic high volume manufacturing plant



imec.netzero



a *Virtual Fab* model for environmental impact assessment

Expand the analysis to:

- Identify **high impact** problems to focus Improve efforts
- Project the **future impact of IC chip manufacturing**

Other technologies:

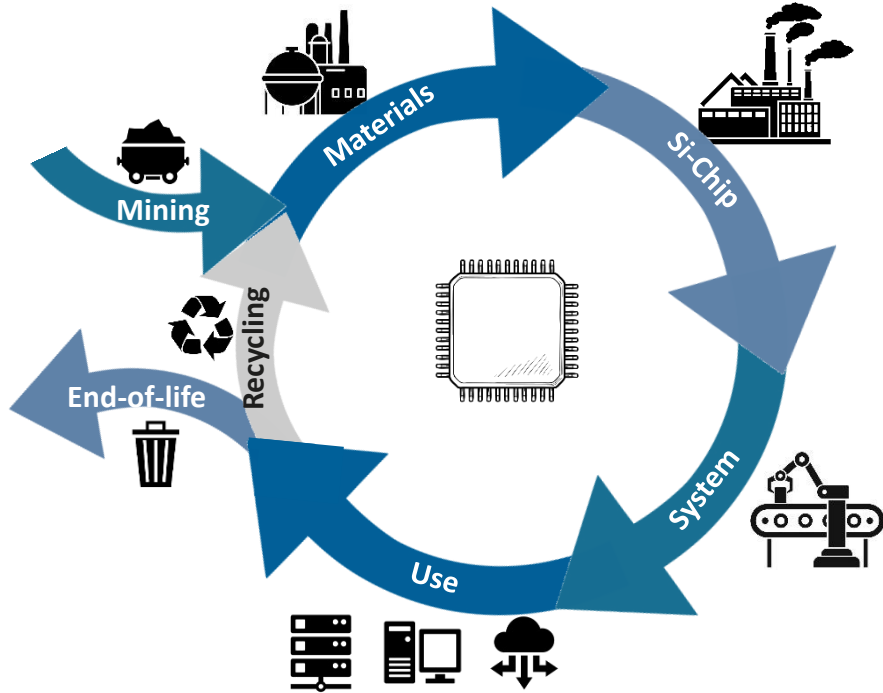
DRAM, 3D NAND, RF, Photonics, 3DIC, imagers

Future extension:

Power Electronics

The life-cycle of a Si-chip

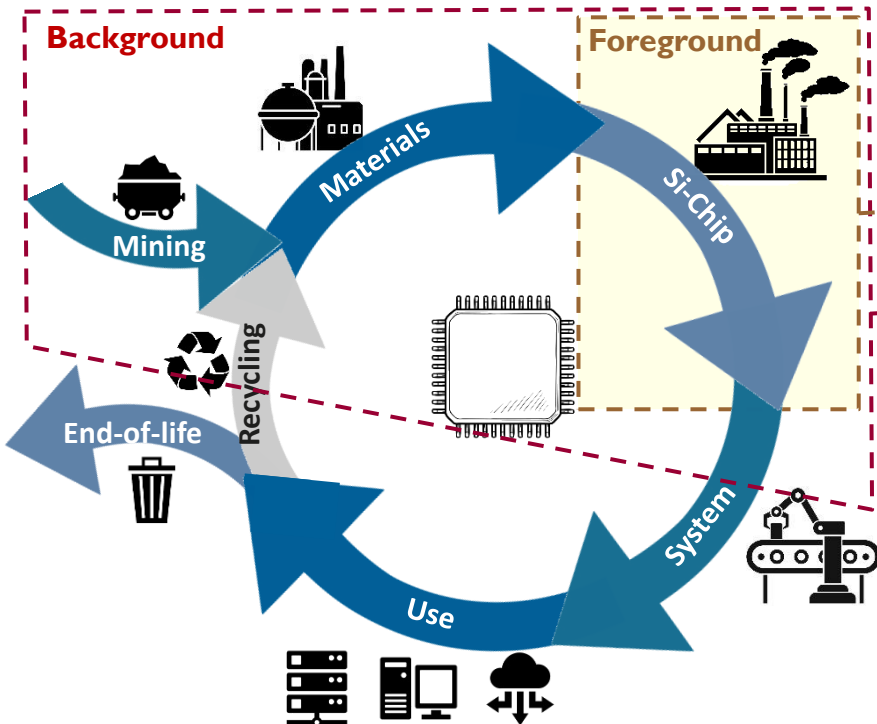
Goal and scope of imec.netzero



- **Product system** – Si chips from HVM
 - Serving several applications (Logic, memory, etc.)
 - Multiple (future) technology nodes
- **Functional Unit**
 - For Manufacturing industry: “per Wafer”
 - For IC Chip users:
 - “per functional die”
 - “per functional cm²”
 - “per transistor” or “per GB”
- **Impact categories**
 - Current focus:
 - Climate Change
 - Abiotic resource depletion
 - Water Usage
 - Under development:
 - Ten EF 3.1 impact categories
 - Normalization per person

The life-cycle of a Si-chip

Goal and scope of imec.netzero



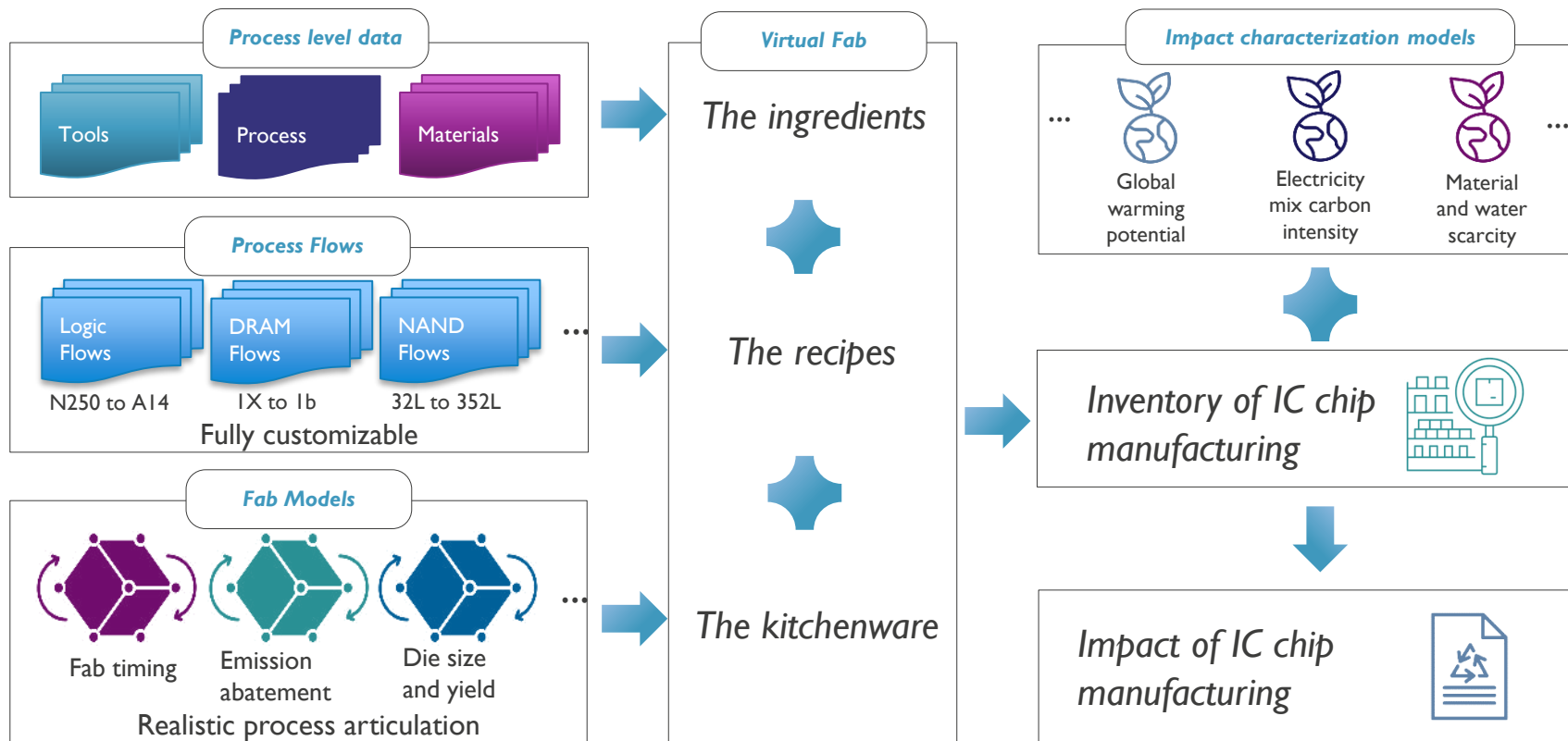
- **Flow** – Covers all operations in generic HVM Fab:
 - Wafer **processing equipment** operation
 - Generation of **utilities**
 - **Infrastructure** operation (clean room, services)

- **System boundaries** – Two sets :
 - **Gate-to-Gate semiconductor (or packaging) Fab**
 - Imec Fab model
 - **Cradle-to-Gate Si-chip manufacturing**
 - Upstream material and electricity flows
 - imec Fab model
 - Downstream chip packaging
 - **Recycling** considered at Fab level, e.g.
 - Recycling ultra-pure water
 - Secondary sourcing of scrap materials

- **Not included**
 - Equipment manufacturing
 - Infrastructure construction

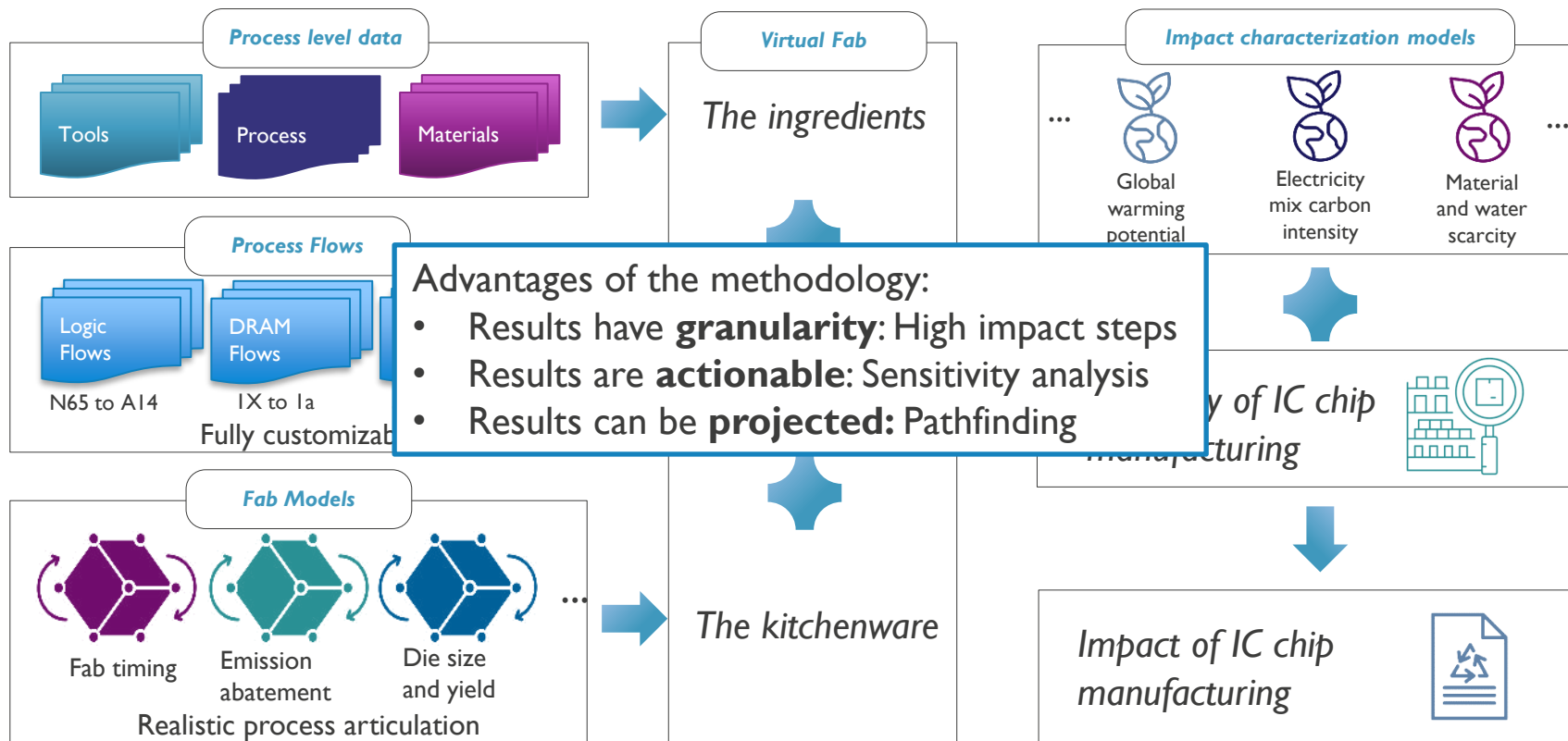
SSTS Assess - Virtual Fab Model

Quantify the footprint of a chip

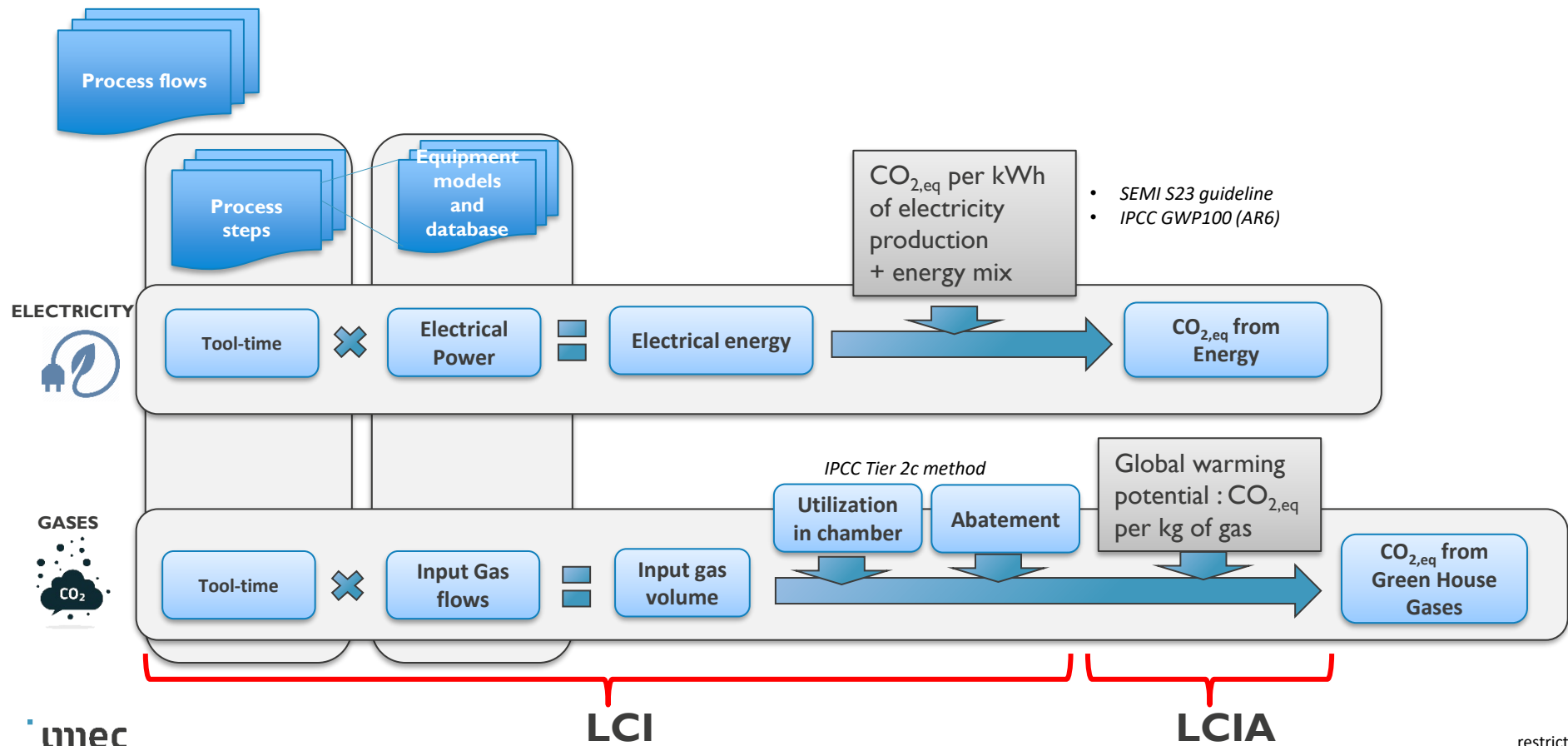


SSTS Assess - Virtual Fab Model

Quantify the footprint of a chip



From process flows to CO_{2,eq} footprint



restricted

Total emissions for logic technology nodes

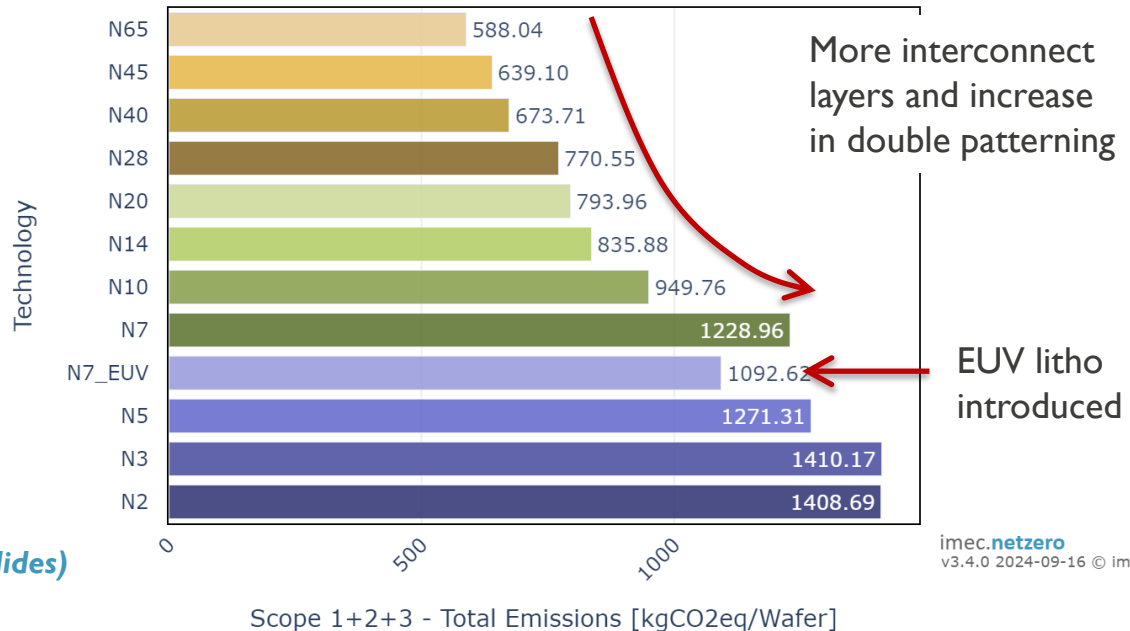
Emission trends for advancing technology nodes

- An increase in the number of process steps directly leads to **increased emissions**
- Introduction of a more advanced lithography process (EUV) reduces the total number of process steps and thus total emissions

INZ default model assumptions (also for all next slides)

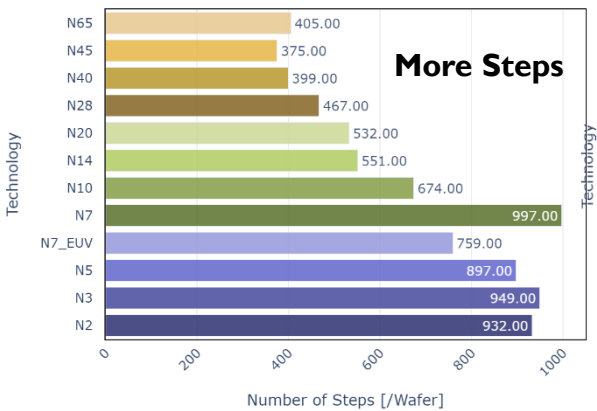
- 100% Production line yield
- 10x10mm² die, Murphy yield with 0,15 defect/cm²
- IPCC Tier 2C Abatement model (2019 Refinement to the 2006 IPCC Guidelines for National Greenhouse Gas Inventories)
- GHG global warming potential from IPCC AR6

Comparison of Scope 1+2+3 - Total Emissions [kgCO₂eq/Wafer] by Technology for full flow (official)

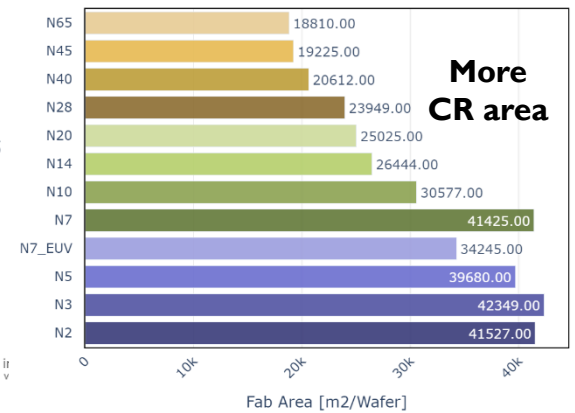


Increasing complexity in Logic nodes

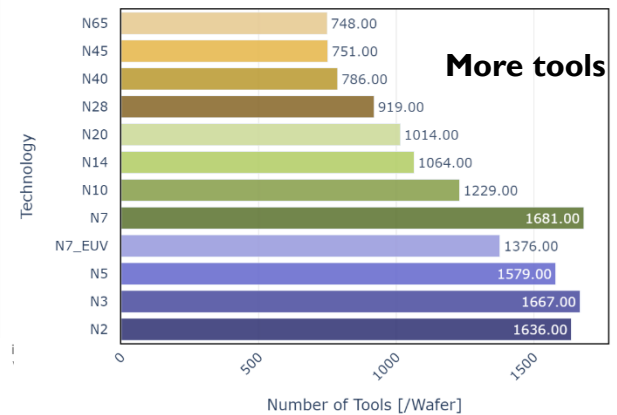
Comparison of Number of Steps [/Wafer] by Technology for full flow (official)



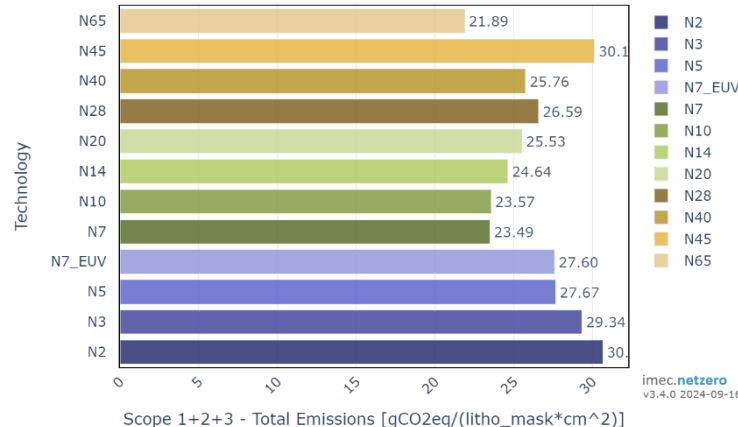
Comparison of Fab Area [m2/Wafer] by Technology for full flow (official)



Comparison of Number of Tools [/Wafer] by Technology for full flow (official)



Comparison of Scope 1+2+3 - Total Emissions [gCO2eq/(litho_mask*cm²)] by Technology for full flow (official)



All numbers for:

- Fab capacity of 60.000 wafers/month
- 70% Tool utilization
- 90% Line yield

Functional unit to compare different technologies:
kgCO2eq / (Mask Layer x cm²)

In this FU footprint is relatively stable.

Hotspots for N28 fab carbon footprint



High dependence on assumptions

Cleanroom view

Total N28 manufacturing emissions
816 kgCO₂e per wafer

Si Wafer
79.4 kgCO₂e
9.7% of total

Dry Etch
171.4 kgCO₂e
21.0% of total

CVD
121.3 kgCO₂e
14.9% of total

Wet clean
100.8 kgCO₂e
12.4% of total


PVD
85.6 kgCO₂e
10.5% of total

EPI
79.1 kgCO₂e
9.7% of total

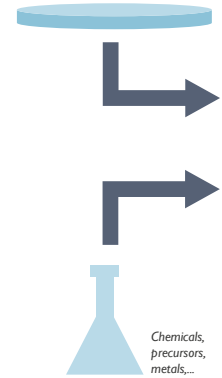
Litho
85.6 kgCO₂e
8.9% of total



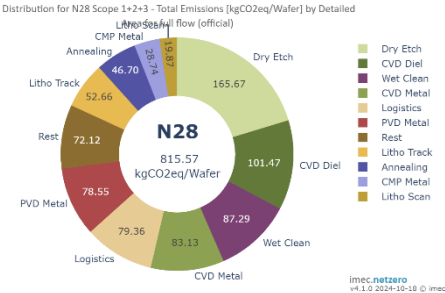
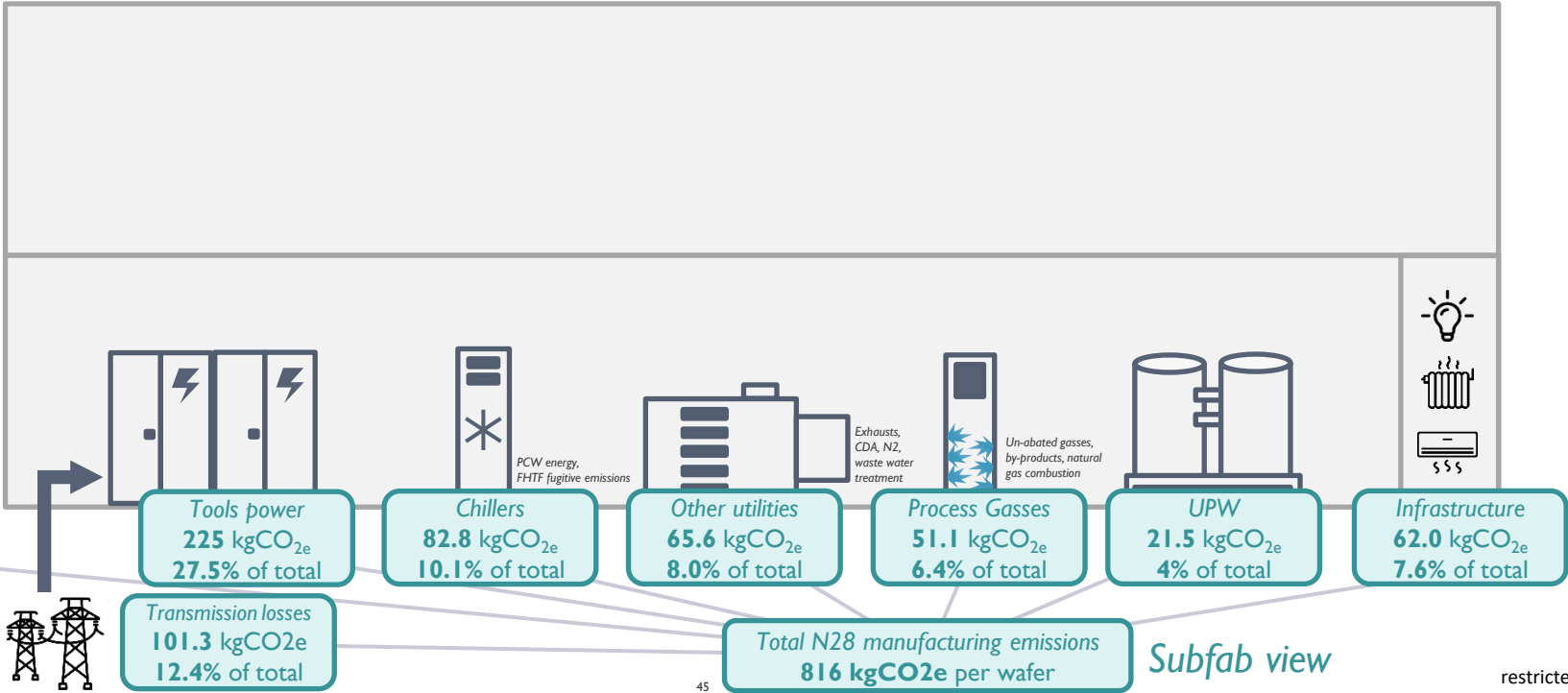
Hotspots for N28 fab carbon footprint

 High dependence on assumptions


Si Wafer
79.4 kgCO_{2e}
9.7% of total



Materials
117.5 kgCO_{2e}
14.4% of total

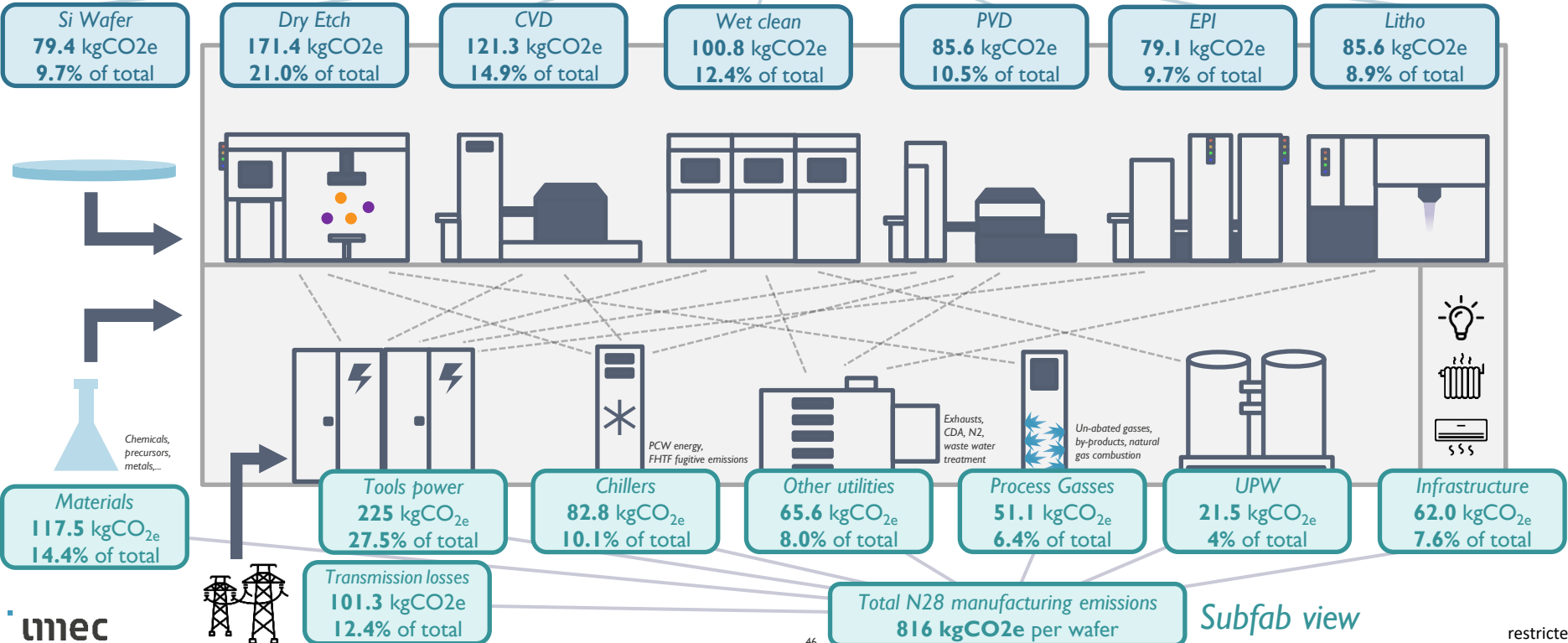
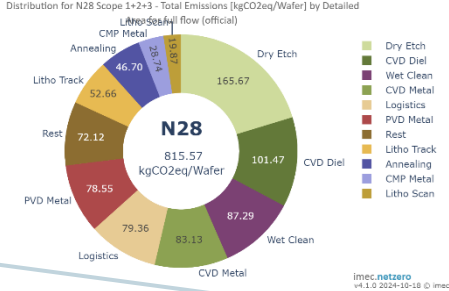


Hotspots for N28 fab carbon footprint

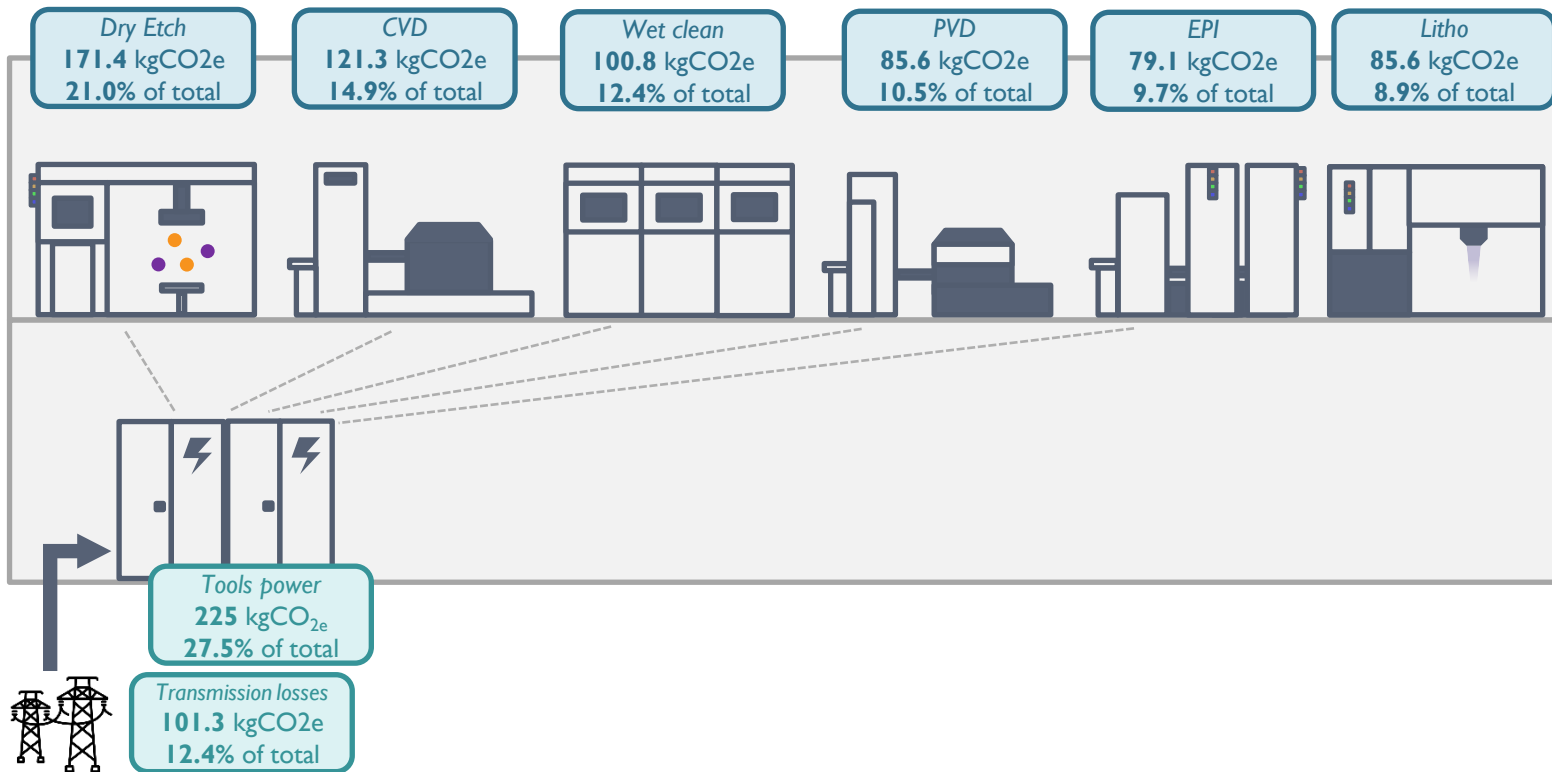
 High dependence on assumptions

Cleanroom view

Total N28 manufacturing emissions
816 kgCO₂e per wafer



Hotspot: tool electrical energy



Hotspot: tool electrical energy

“Subfab view”



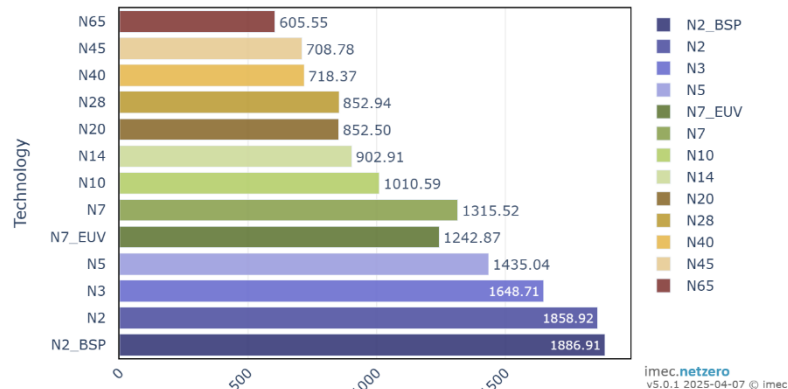
- Electricity needs of semiconductor fabs are very high
 - Typical tool power rating range 5..50 kW (up to 1MW for EUV litho)
 - HVM fabs need several hundreds of tools

- High dependence on electricity mix of fab
 - “Industry average” = 500gCO₂e/kWh
 - “Clean grid” < 100gCO₂e/kWh

- Transmission losses on the grid are significant



Comparison of Full Electric Energy Consumption [kWh/Wafer] by Technology for full flow (official)



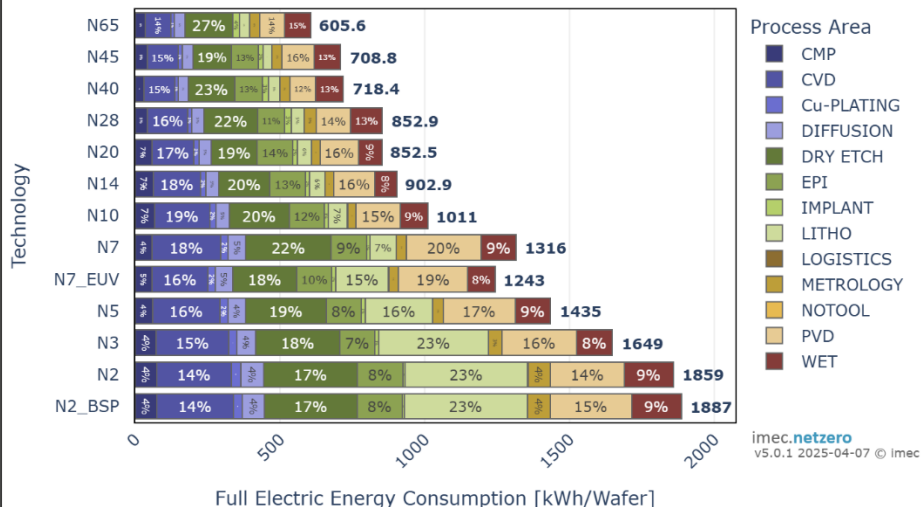
Full Electric Energy Consumption [kWh/Wafer]



Hotspot: tool electrical energy

“Cleanroom view”

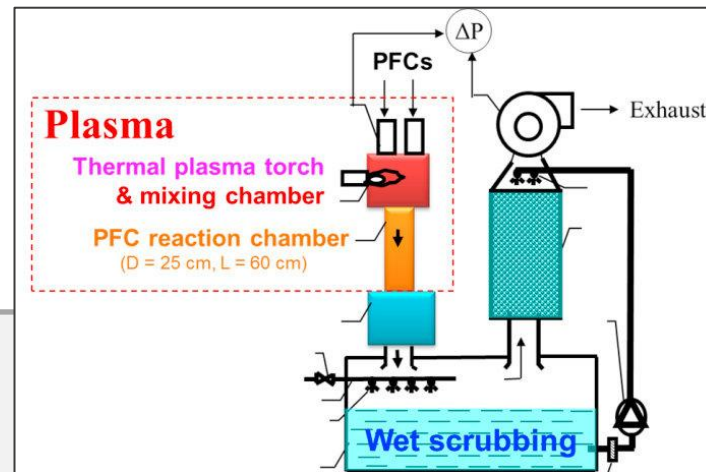
Comparison of Full Electric Energy Consumption [kWh/Wafer] by Technology & Process Area for full flow (official)



- Many process areas require lots of energy
 - Deposition processes
 - CVD
 - EPI
 - PVD
 - Dry Etch
 - Litho (post-EUV)
 - Wet cleans
- Driving factors: high temperatures, long processes, giant lasers, water heating/cooling, ...

Hotspot: process gas emissions

Dry Etch
171.4 kgCO₂e
21.0% of total



Un-abated gasses,
by-products, natural
gas combustion

Process Gases
51.1 kgCO₂e
6.4% of total

Hotspot: process gas emissions

“Subfab view”

- Semiconductor manufacturing uses some extremely strong GreenHouse Gases
 - Strong radiative forcing
 - Very stable, lifetime in the atmosphere: several **thousands of years**
 - Usual unit: GWPI100 = relative warming effect to 1kg of CO2 during 100 years

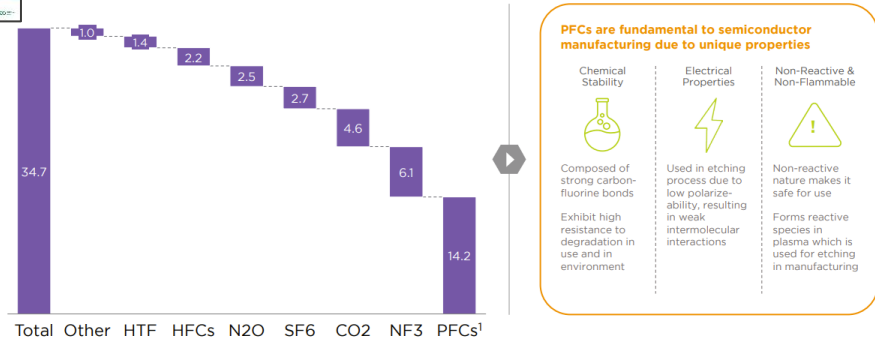
gas	GWPI ₁₀₀
SF6	25 200
NF3	17 400
CF4	6 630
C2F6	12 400

Releasing 1 kg of SF6 into the atmosphere has the same warming effect over 100 years as releasing 25 200kg of CO2!

- Abatement technologies exist
 - Combustion- or plasma-based
 - Destruction and Removal Efficiency up to 95~99%



Exhibit 6: Direct semiconductor manufacturing emissions (Mt CO₂e, 2021)

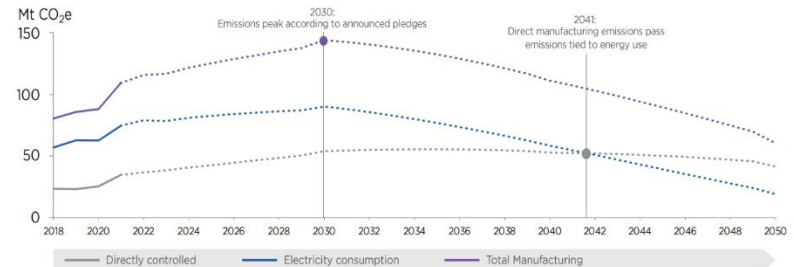


Acronyms: Heat Transfer Fluids, Hydrofluorocarbons, Nitrous Oxide, Sulfur Hexafluoride, Carbon Dioxide, Nitrogen Trifluoride, Perfluorinated Compounds. ¹ PFCs include carbon tetrafluoride (CF₄), hexafluoroethane (C₂F₆), fluoromethane (CHF₃), octafluoropropane (C₃F₈), octafluorocyclobutane (C₄F₈). Source: CDP, ECHA, BCG analysis

09

Exhibit 8:

With current announced pledges by governments and companies, direct emissions from manufacturing will surpass those from electricity use by 2041



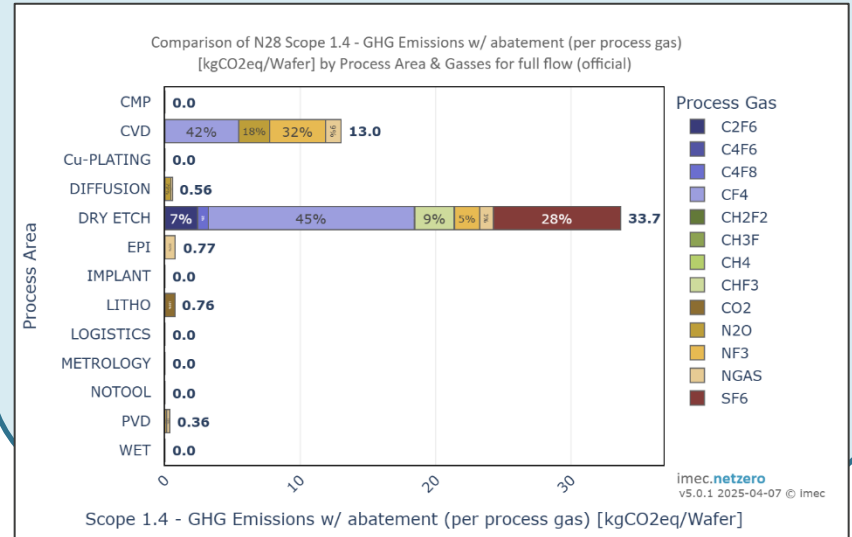
Note: Forecast uses IEA STEPS for North America, Europe, and Asia-Pacific
Source: BCG analyses on data from CDP, Imec, SEMI, IEA

Hotspot: process gas emissions

“Cleanroom view”

- Semiconductor manufacturing uses some extremely strong GreenHouse Gases
 - Strong radiative forcing
 - Very stable, lifetime in the atmosphere: several **thousands of years**
 - Usual unit: GWPI00 = relative warming effect to 1kg of CO2 during 100 years
- Abatement technologies exist
 - Combustion- or plasma-based
 - Destruction and Removal Efficiency up to 95~99%

- Most high GHG are used for etching
 - A fraction of the gas is not used and exits
 - Other GHG are generated as byproducts
- Also appears in some deposition processes
- NF3 used as clean gas

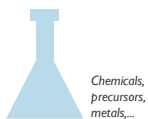


Hotspot: upstream impacts



- Si Wafer manufacturing requires high temperatures
- Many materials and chemicals needed (way more than what ends up on the wafer), with very high purity requirements
 - Difficult to estimate!

Si Wafer
79.4 kgCO_{2e}
9.7% of total



Materials
117.5 kgCO_{2e}
14.4% of total

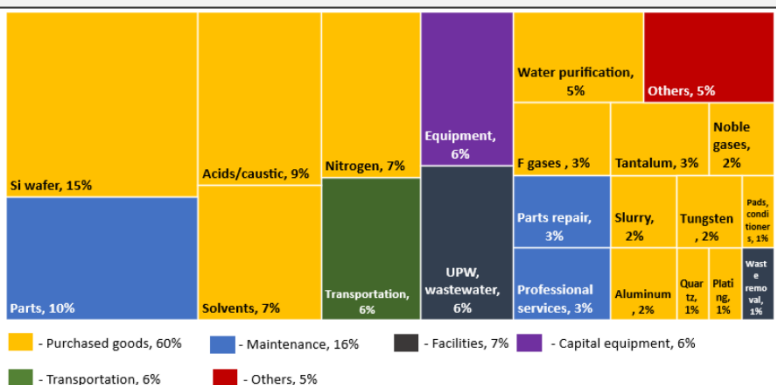
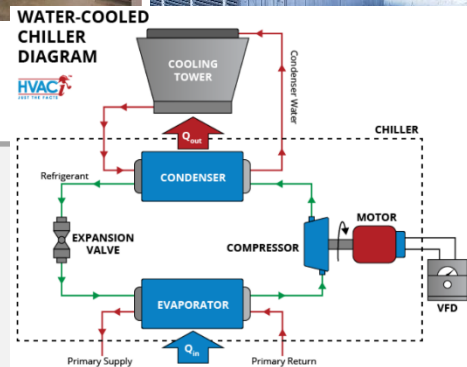
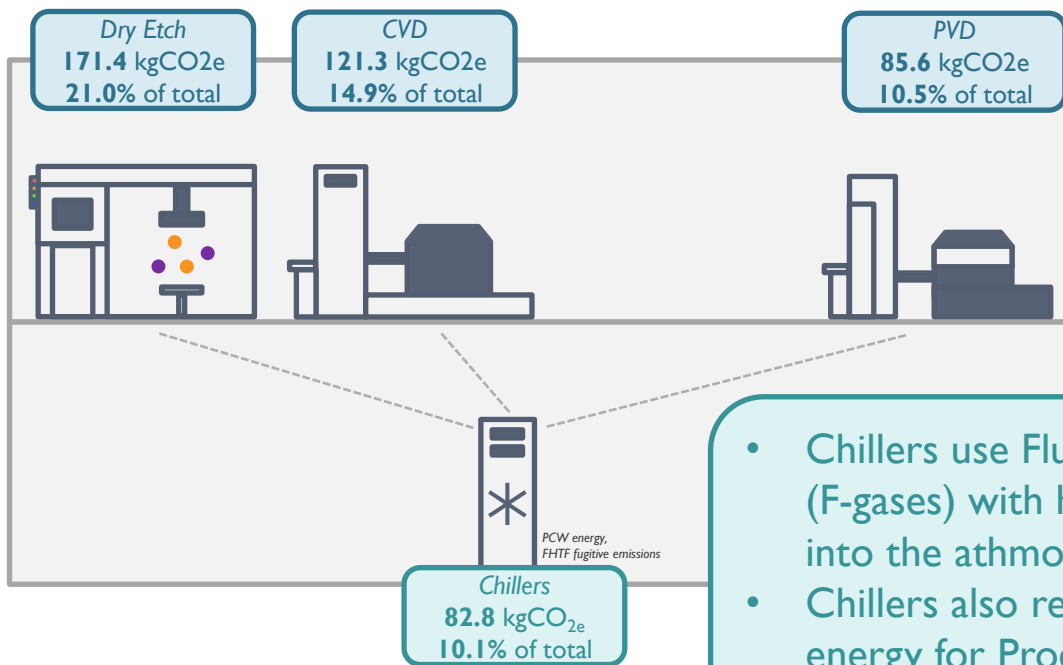


Figure 7. Breakdown of Scope 3 emissions for semiconductor companies [28].

Hotspot: cooling

All the heat generated must be evacuated from the fab

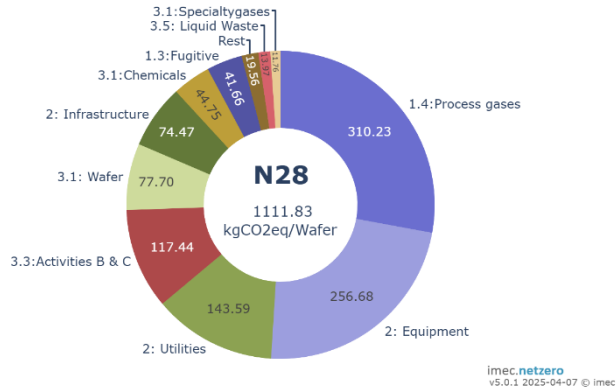


- Chillers use Fluorinated Heat Transfer Fluid (F-gases) with high GWP that eventually leak into the atmosphere
- Chillers also require large amounts of energy for Process Cooling Water

Existing and prospective solutions

Solutions?

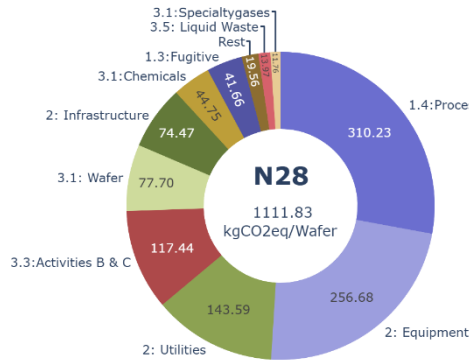
There are many low-hanging fruits already



Taiwan electricity mix
25% abatement deployment

Solutions?

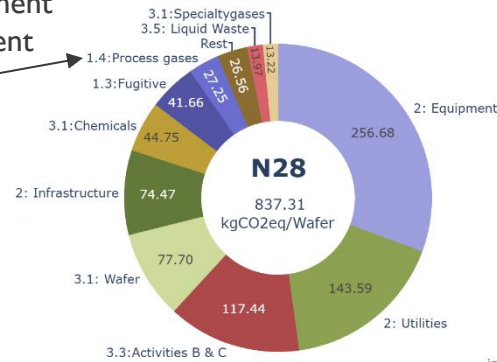
There are many low-hanging fruits already



Taiwan electricity mix
25% abatement deployment

Full abatement deployment

imec.netzero
v5.0.1 2025-04-07

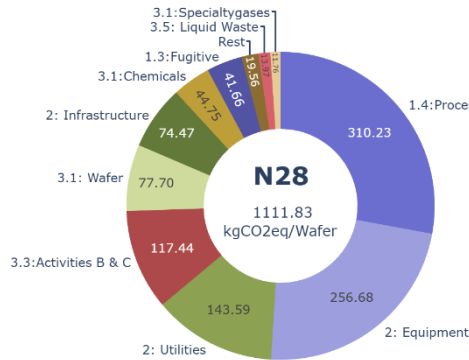


Taiwan electricity mix
100% abatement deployment

imec.netzero
v5.0.1 2025-04-07 © imec

Solutions?

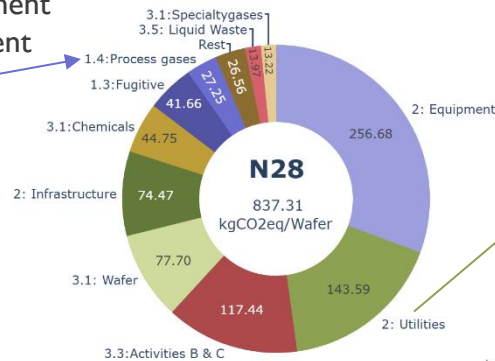
There are many low-hanging fruits already



Taiwan electricity mix
25% abatement deployment

Full abatement deployment

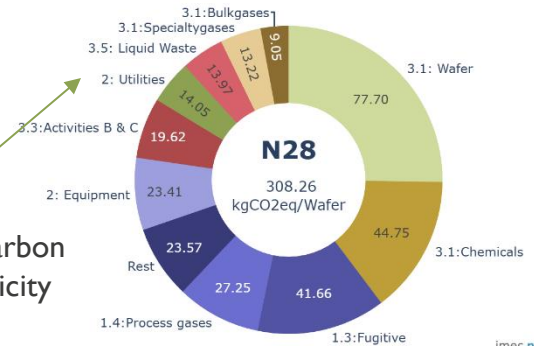
imec.netzero
v5.0.1 2025-04-07



Taiwan electricity mix
100% abatement deployment

Low-carbon electricity

imec.netzero
v5.0.1 2025-04-07 © i

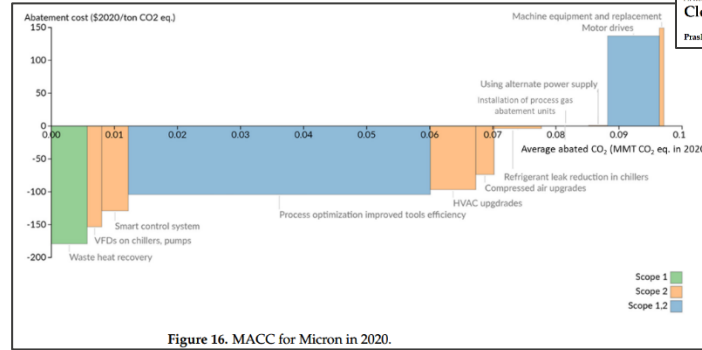
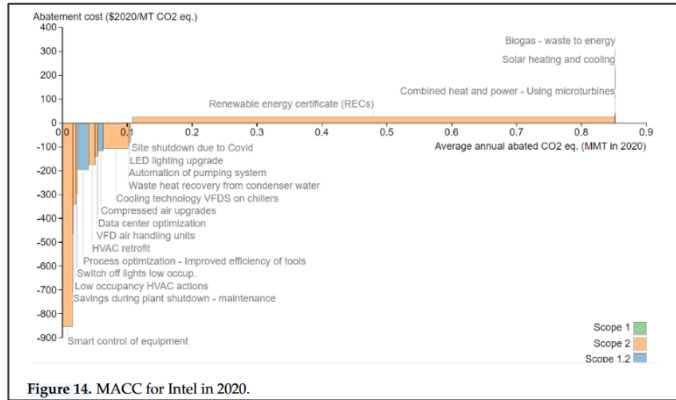


French electricity mix
100% abatement deployment

imec.netzero
v5.0.1 2025-04-07 © imec

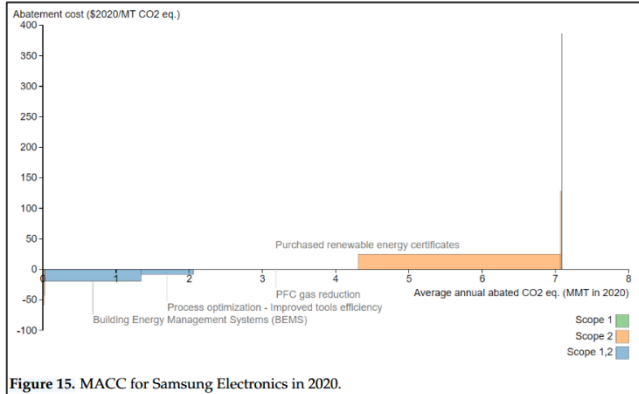
Solutions?

Challenges are (i) deployment at scale...



sustainability

Article
Cleaner Chips: Decarbonization in Semiconductor Manufacturing
Prashant Nagapurkar, Pooja Nandy and Sachin Nimbalkar



Cost & Environment savings (win-win):

- Energy efficiency and tool upgrades
- Smart processes (optimization)
- Leak reductions
- Waste (material and energy) recovery
- ...

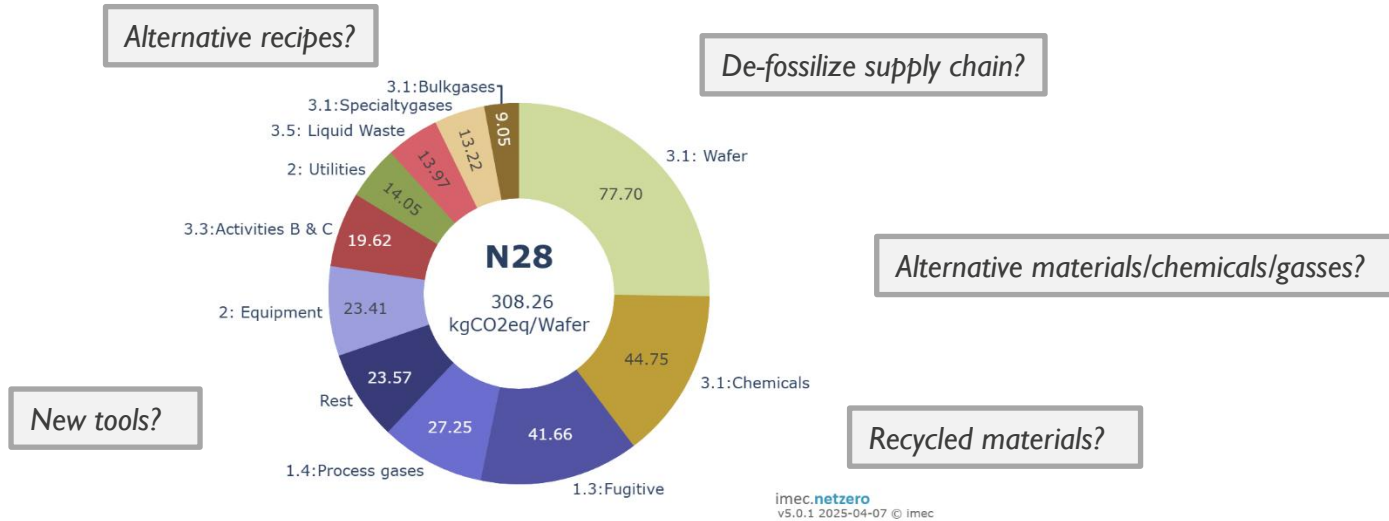
vs.

Cost-Environment tradeoff (need regulation?)

- Abatement
- Waste treatment
- Renewable electricity (depends...)
- Electrification of some processes
- ...

Solutions?

Challenges are (ii) remaining emissions



All this is happening already, but slow in a **risk-averse** and **highly complex** industry...

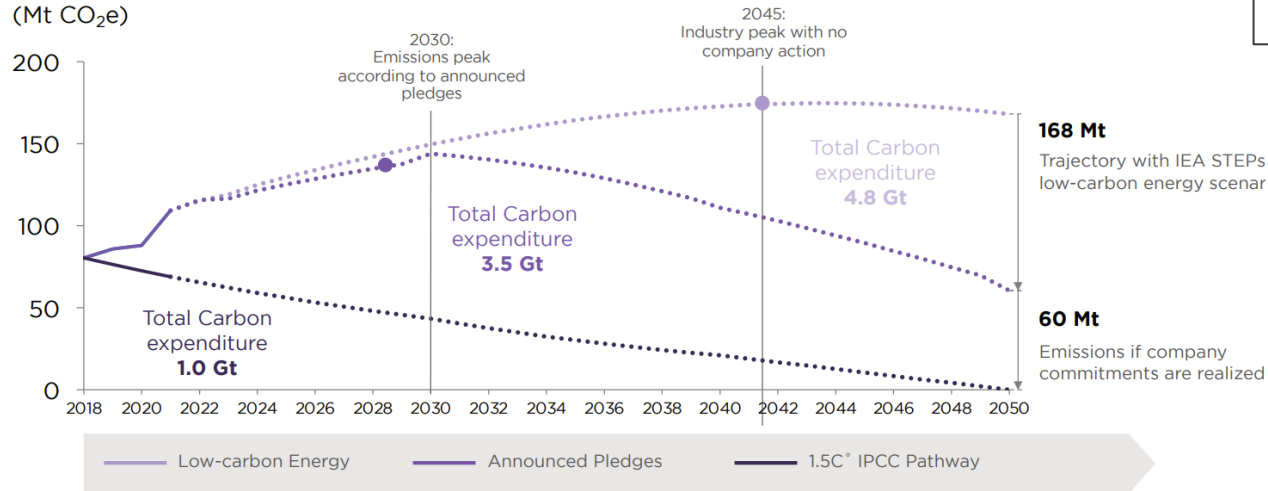
Solutions?

Challenges are (iii) absolute impact reduction

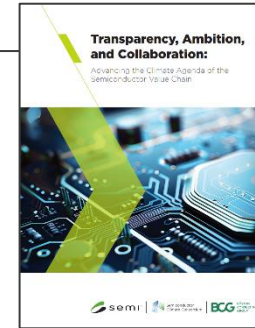
Exhibit 7:

Announced sustainability pledges reduce total 2019–2050 emissions by 30% and are within 60 Mt CO₂e of 2050 net zero

Manufacturing Emissions
(Mt CO₂e)



1 Emissions growth based on projected capacity growth (3.25%) and average intensity growth (1.01%), all else constant
Note: Low-carbon energy scenarios use IEA STEPs for North America, Europe, and Asia-Pacific. Source: BCG analyses on data from: CDP, imec, SEMI, IEA



Need for complementary lesser or non-technical solutions? E.g.

- *Incentives/regulations*
- *Other business models*
- *Other consumer habits*

Solutions?

Challenges are (iv) **Environmental metrics deployment in innovation phase**

- Innovation is not driven by sustainability staff but by **expert from the field**.
- Provide **specifications** on environmental impact to engineers
 - Sufficiently **early in the innovation phase**
 - **Acceptable**: Understandable, defensible
 - **Accessible**: User friendly tool for computing
- **E-score** to complement Power-Performance-Area-Cost **PPAC** scorecard. See next section.



Environmental Scoring: A spec to guide innovation

Motivation for E-score tool development

Goals and ambitions

- Main goal for E-score: **infuse the sustainability concern in all innovation processes** at the heart of semiconductor manufacturing technologies. Early-stage embedment in R&D will drive **maximum impact on our industry**.
- Innovation in semiconductor industry is driven by the Power Performance Area and Cost (PPAC) scorecard. With E-score, we want to **add an Environmental (E) metric to the card that becomes:**

PPAC-E

- The deployment of E-score is three-pronged:



E-Metric for PPAC

*A defensible metric anchored
in Environmental Science
practices*



Toolbox for quantification

*A platform for E-score
quantification combining
flexibility with user-friendliness*



Dissemination

*For early platform
adoption, feedback
and rapid spreading*

E-score: Inventory

Using a real example from an etch stack evaluation

1. Inventory:

- **Life Cycle Inventory (LCI)**
- **Provides concrete information,**
- **No bias applied**

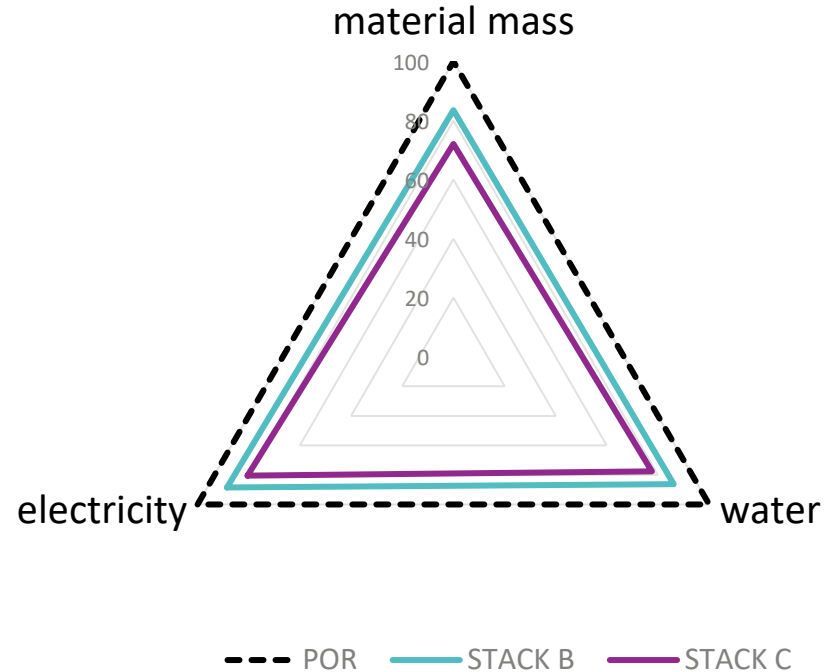
2. Impact

- Life Cycle Impact Assessment
- Convert inventory to impact
- Slightly harder to communicate in fab

3. Normalization

- Enables comparison of different impacts
- Common unit
- Enables a single E-score

4. Weighting



POR is the reference process of record being compared to two options

E-score: Impact analysis

Real example based on Dry Etch stack Improvement

1. Inventory:

- Life Cycle Inventory (LCI)
- Provides concrete information,
- No bias applied

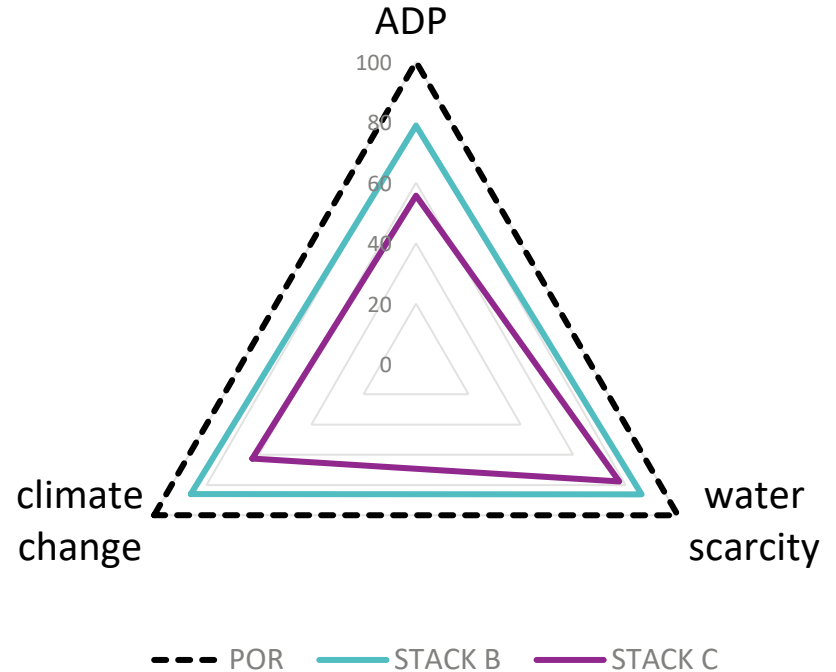
2. Impact

- **Life Cycle Impact Assessment**
- **Convert inventory to impact**
- **Slightly harder to communicate in fab**

3. Normalization

- Enables comparison of different impacts
- Common unit
- Enables a single E-score

4. Weighting



E-score: 3. Normalization

Real example based on Dry Etch stack Improvement

1. Inventory:

- Life Cycle Inventory (LCI)
- Provides concrete information,
- No bias applied

2. Impact

- Life Cycle Impact Assessment
- Convert inventory to impact
- Slightly harder to communicate in fab

3. Normalization

- **Enables comparison of different impacts**
- **Common unit**
- **Enables a single E-score**

Normalization Factor (NF_i): average impact of 1 person per year for one specific impact category i :

$$NF_i[\text{unit}_i/\text{person}] = \frac{\text{Global Impact } i \text{ (2010)}[\text{unit}_i]}{\text{Global Population (2010)}[\text{person}]}$$

Normalization gives a **unit of person**

Weighting gives a **unit of points**
(Equal weighting considered here)



data collection
@planet scale

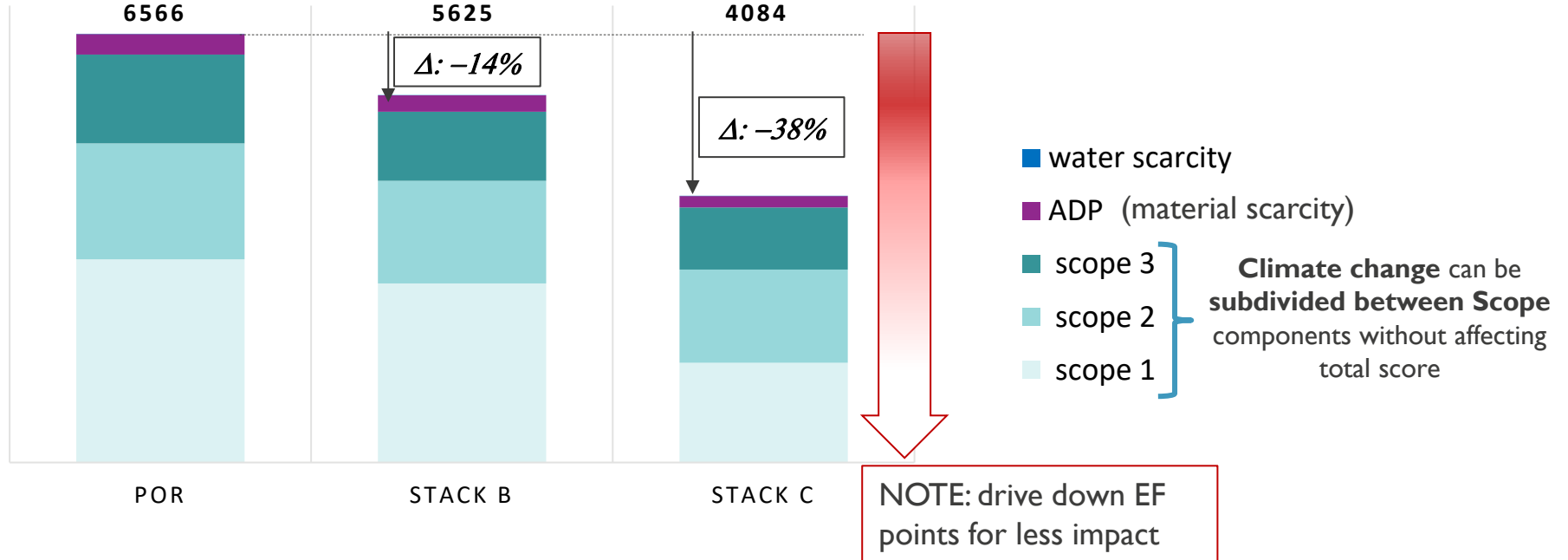


~6.9 billion
In 2010

E-score: Concatenation to single E-score

Real example based on Dry Etch stack Improvement

E-score version 1 (EF points **per million wafers**)



Conclusion

Take home messages

And remember:

- Environmental sustainability does not stop at climate change
- Sustainability does not stop at environmental sustainability

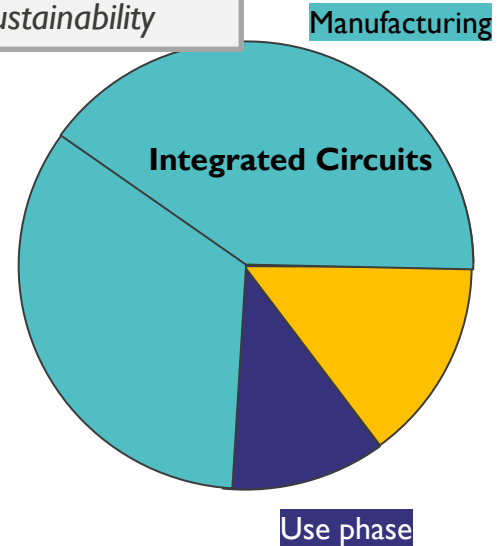
The climate change impact of IC chip manufacturing is still expected to increase in the future. The industry needs to **work hard to fulfill their pledges and further to achieve net zero by 2050**

The impact of **IC chip manufacturing** is one of the **largest contributors** to the **carbon footprint of ICT devices**:

- Low entropy products from highly complex value chain
- One of highest carbon footprint/ mass ratios
- Consumes massive amount of electricity and high purity materials

The total climate change impact of IC manufacturing can be reduced by:

- Effective **abatement** on high GWP process gases
- **Non-fossil-based electricity** sources
- **De-fossilize supply chain**, specifically Si wafer production
- Adoption of **environmental scoring metrics** early in the technology design phases



What can you do (as an engineer)?

“If you are not part of the solution, you are part of the problem”...?

- **Think holistically about the implications of what you do**
 - For environmental impacts, Life-Cycle Analysis is the standard
 - LCA can be time-consuming, but is flexible in scope/accuracy (better be inaccurate than blind)
 - Don't forget to also think beyond LCA (rebounds, societal impacts, ...)
- **How to do “eco-design”?**
 - General principles abound (circularity, absolute sustainability, doughnut economy, regenerative, low-tech, ...)
 - At-scale examples are rarer (on the surface ...) but do exist
 - It's up to you now!
- **Instead of efficiency optimization aim for resilience:**
 - Resilient systems are sub-optimal but adaptative: “From better to good enough”



mec

embracing a better life